

J.A. Woollam Co., Inc.

Ellipsometry Solutions

1A: Introduction to WVASE Data Analysis

Nina Hong

U Penn, February 2014

Session Outline

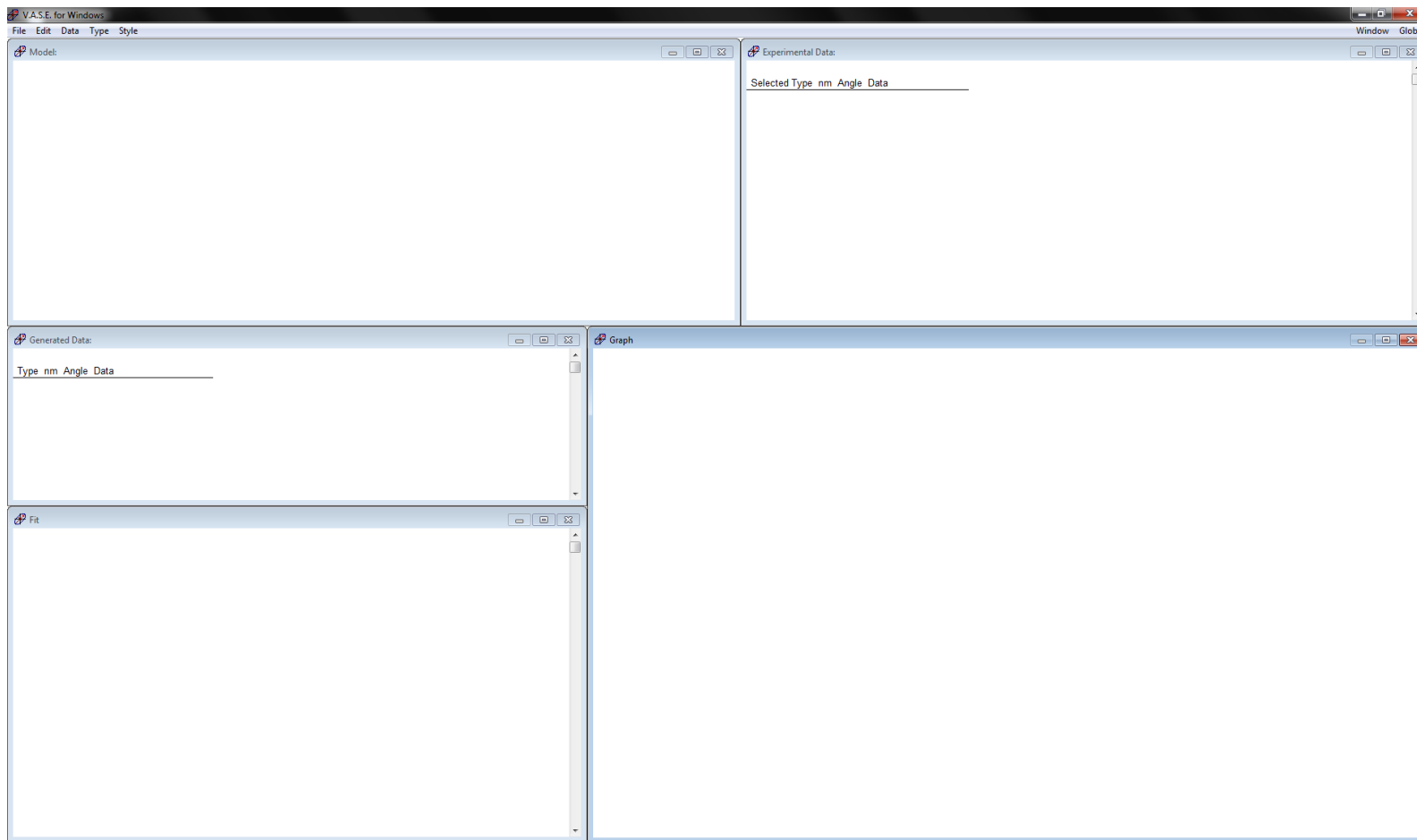
- 1. Introduction to Ellipsometry.**
- 2. Classification of Samples.**
 - Transparent
 - Semi-absorbing
 - Absorbing
 - Bare substrates, and coated samples.
- 3. Oscillator Models and Genosc Layer.**
 - Types of oscillators.

Learning Outcomes:

- Basic operation of WVASE software.
- Fundamentals of spectral interpretation.

WVASE Software

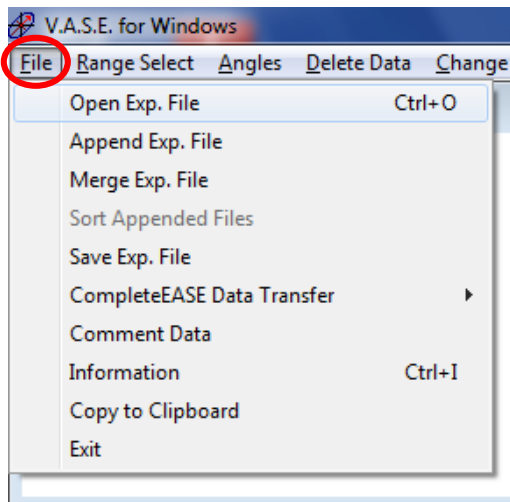
Opening Screen.



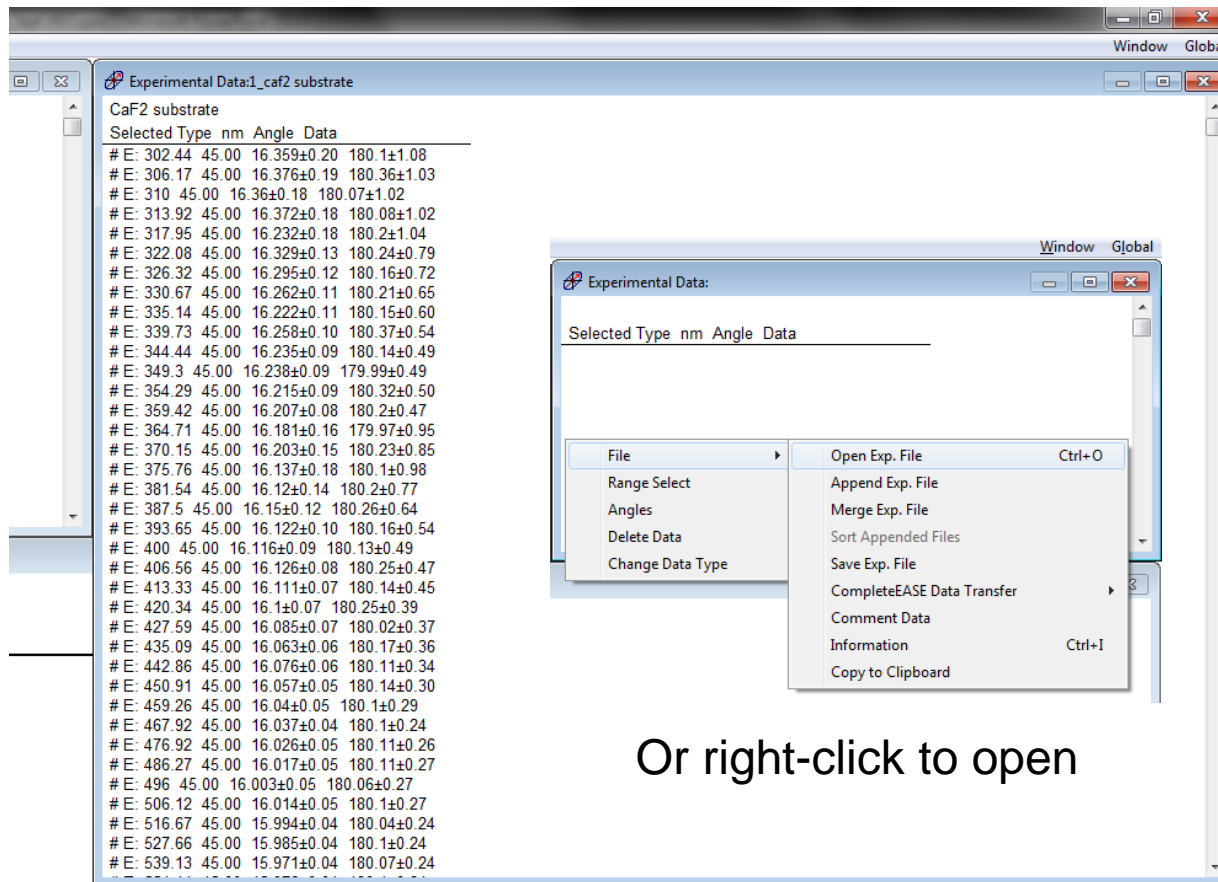
Five Empty Windows. Click inside each.
How to use these windows?

Experimental Data Window

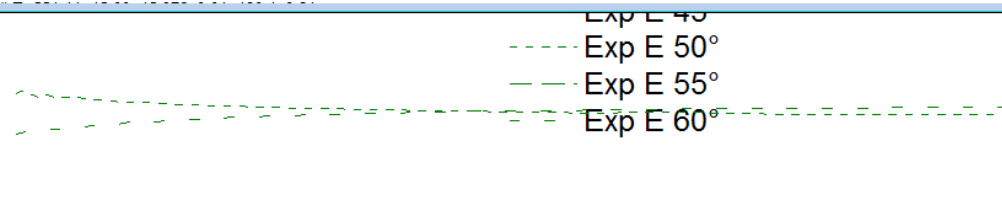
Use to open data files.



From upper-left.

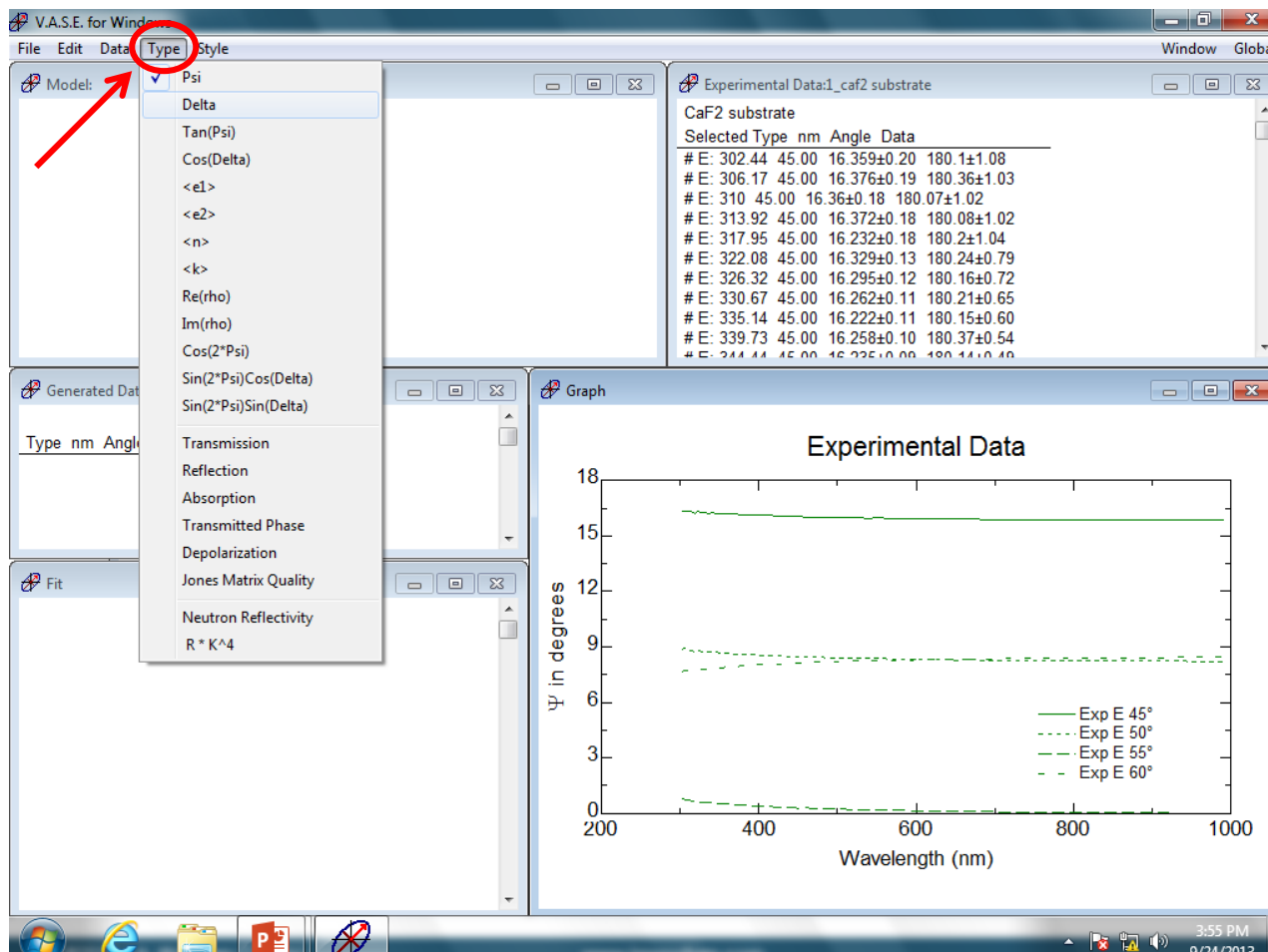


Or right-click to open



Graph Window

Displays graphs of Experimental Data



Select "Type" to change graphs.

Step 1:

- Select Experimental Data Window.
- Open data file: 1_CaF2 Substrate.dat

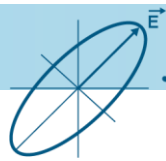
Step 2:

Select Graph Window

- **Plot Ψ and Δ data.**
- Ψ and Δ ? **What are these?**
- **What do they mean?**

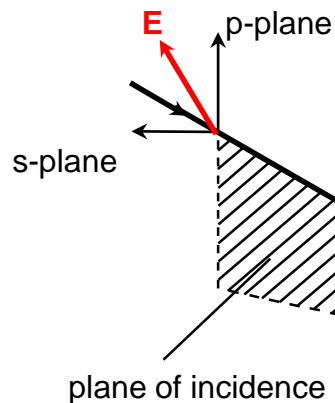
Learning Outcomes:

- Use Experimental Data and Graph Windows.
- Open data files. Display graphs of Ψ and Δ .

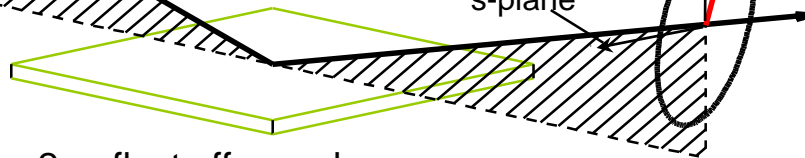


Ellipsometry Measurement

1. linearly polarized light ...



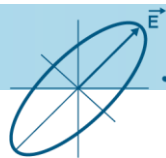
2. reflect off sample ...



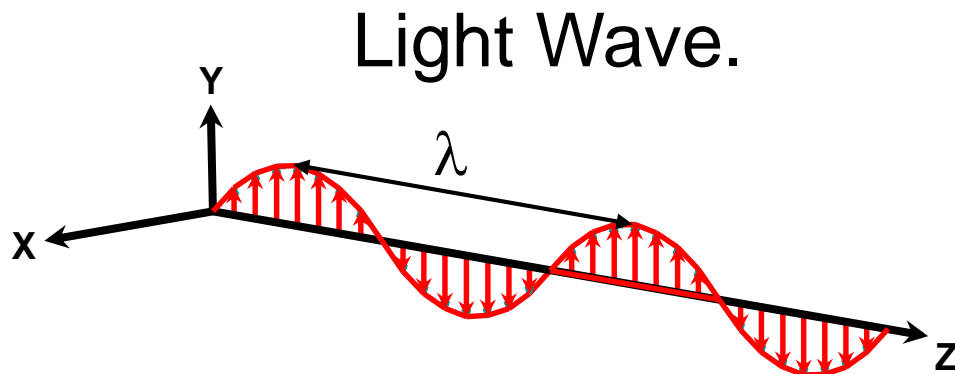
3. elliptically polarized light!

- Ellipsometry **measures the change in polarization state** of light reflected from a surface.
- Sample properties cause the change.
- Polarization is rotated, and becomes elliptical.

Next: What is polarized light? What is Ellipsometry?



Units: Wavelength, Photon Energy, & Wavenumber

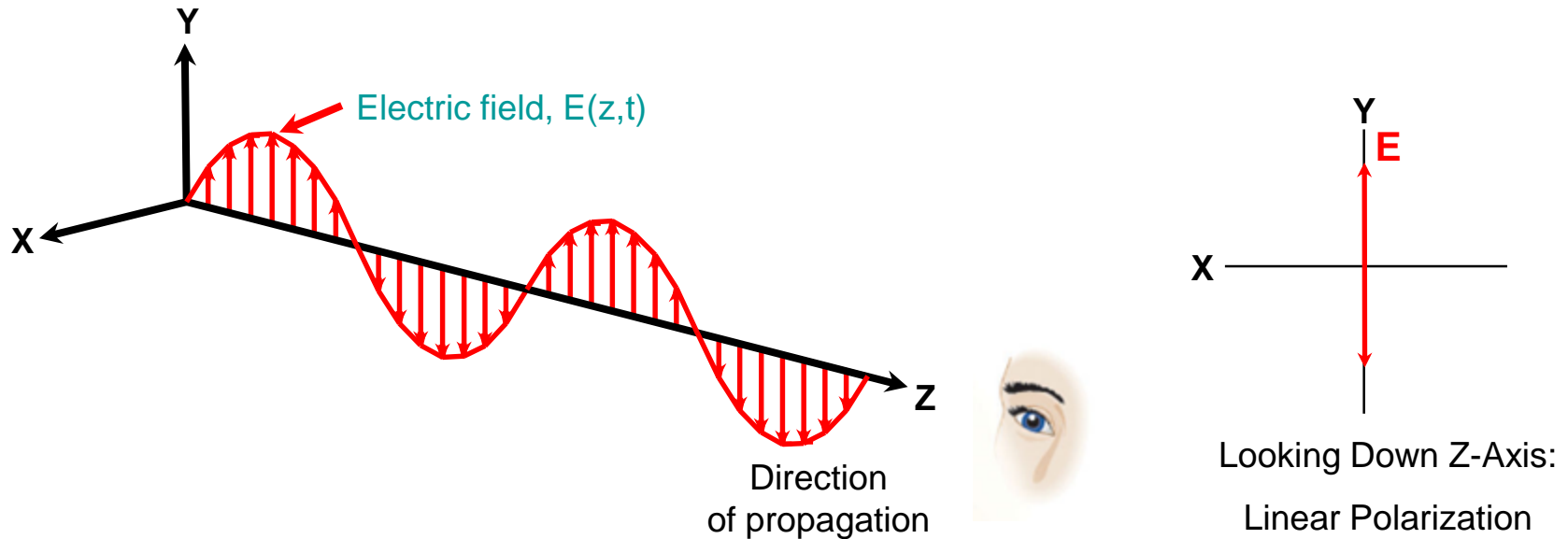


- **Wavelength**, λ (units in Å, nm, or microns)
- **Photon Energy** (eV). “Electron Volts”
- **Wavenumber** (cm^{-1}). Used Mid to Far IR.
- Unit conversions:

$$E_{eV} = \frac{12400}{\lambda_{\text{Å}}}, \quad E_{eV} = \frac{1240}{\lambda_{\text{nm}}}, \quad E_{eV} = \frac{1.240}{\lambda_{\mu\text{m}}}, \quad \text{cm}^{-1} = \frac{10000}{\lambda_{\mu\text{m}}}$$

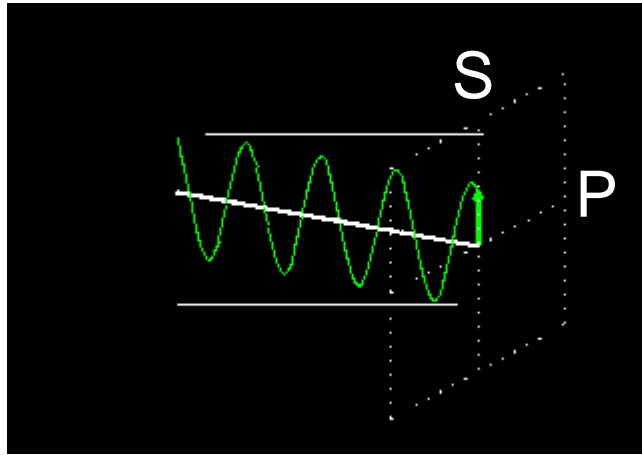
What is Polarization?

- “Shape” of the beam as it propagates towards us. (Looking down z-axis).

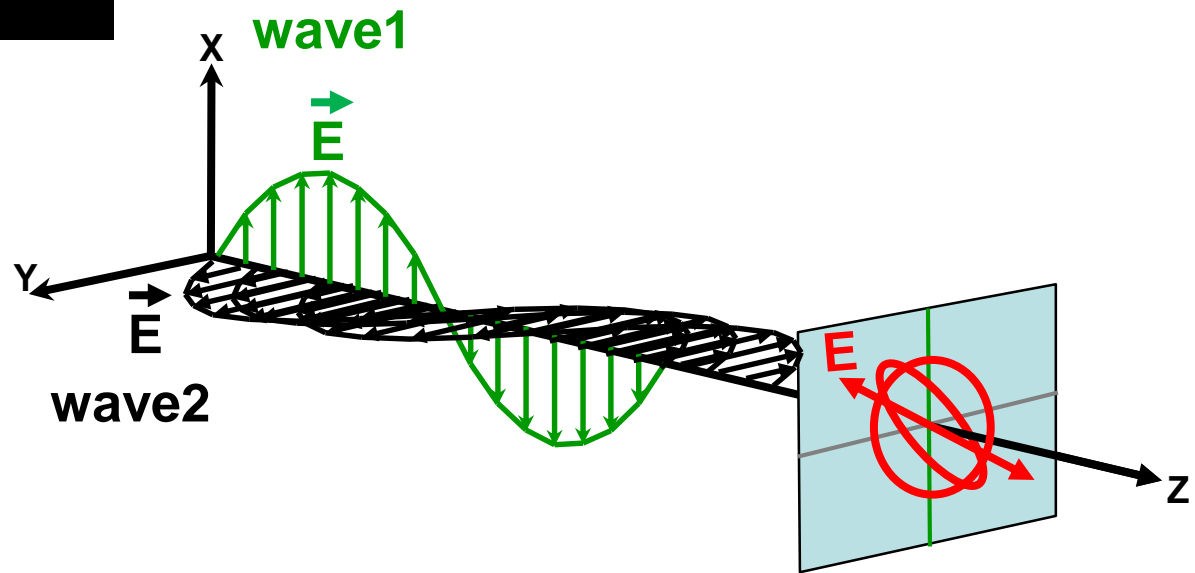
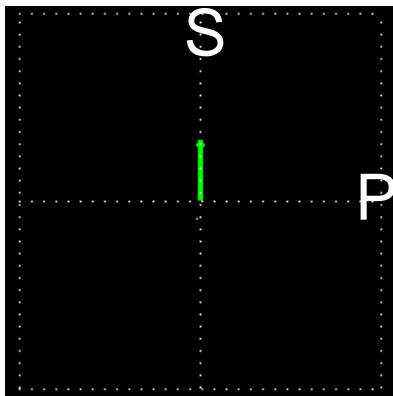


- Polarization state defined by orientation & phase of the E-field vector.

Polarized Light



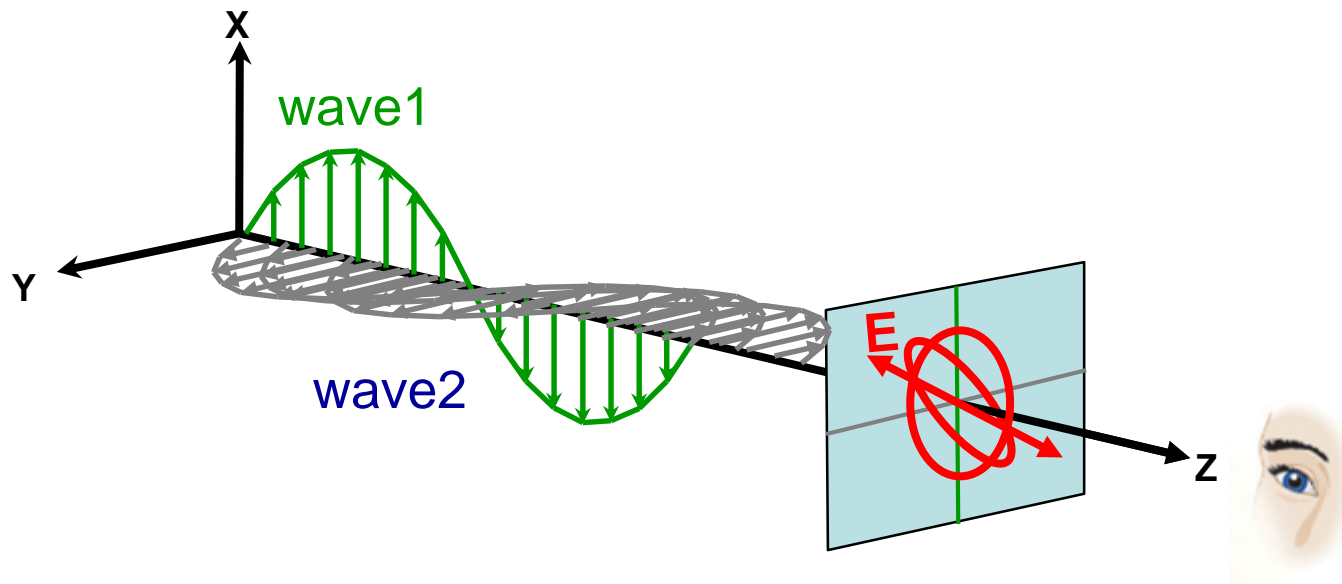
- Polarization can be linear, circular or elliptical.
- *Superposition* of two orthogonal light beams (components).



ANIMATIONS FROM WWW.ENZIM.HU
 ACCESSED JUNE 6, 2012

What is Polarization?

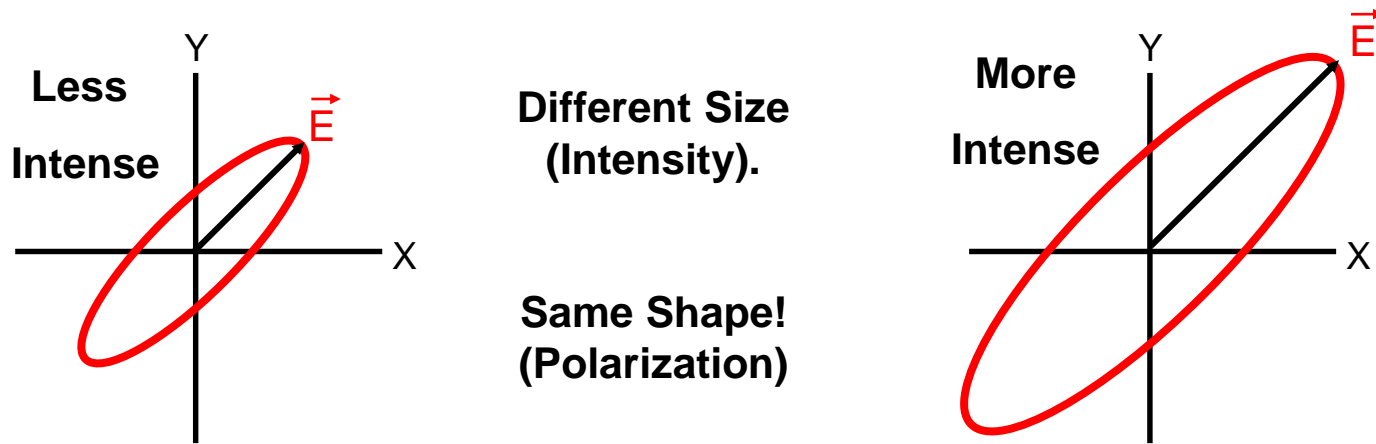
Polarization: Describes “shape” of electric field along the direction of travel.



- **Linear**: arbitrary amplitudes, in-phase.
- **Circular**: equal amplitudes, 90° phase difference.
- **Elliptical**: arbitrary amplitudes, arbitrary phases.

Intensity and Polarization

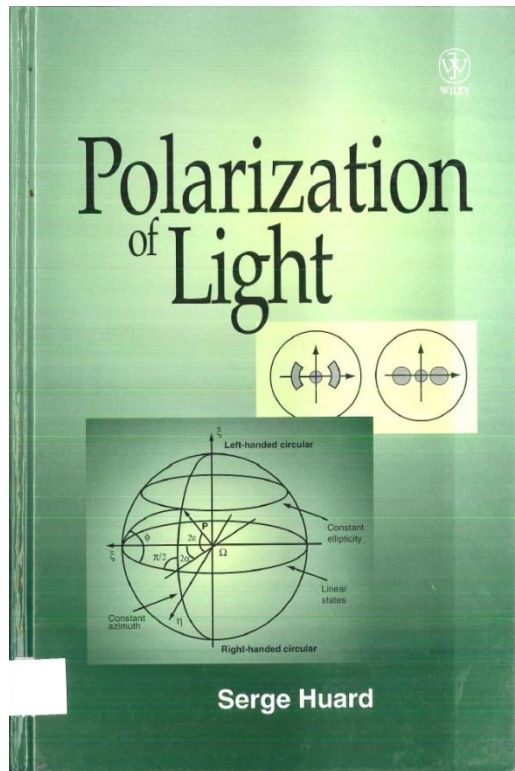
- Light Intensity = **“Size” of the Ellipse.**
 - One Number Describes Wave Amplitude (E).
 - Intensity is proportional to E^2 ... “Brightness”. $I \propto E^2 = (E_x^2 + E_y^2)$



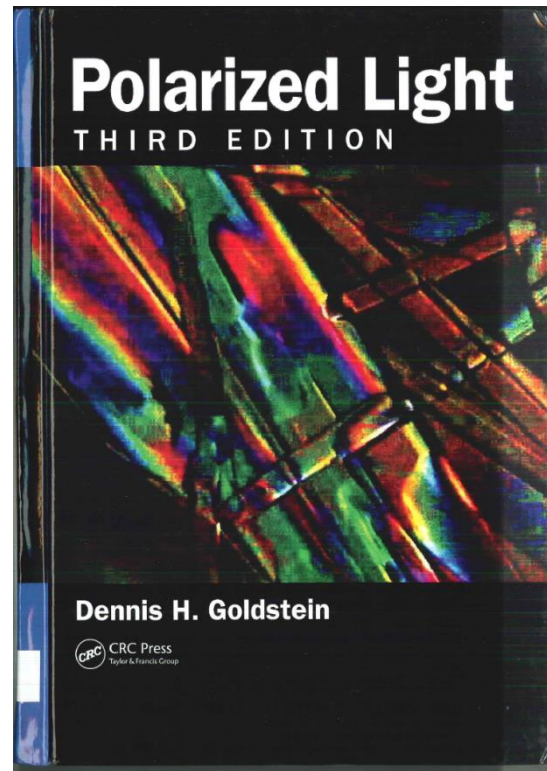
- Polarization = **“Shape” of Ellipse.**
 - **2 numbers required:** ellipse **Azimuth and Ellipticity.**
 - Independent of ellipse size. Independent of intensity
 - **Ellipsometry always measures 2 numbers: Ψ & Δ .**

Light and Polarization

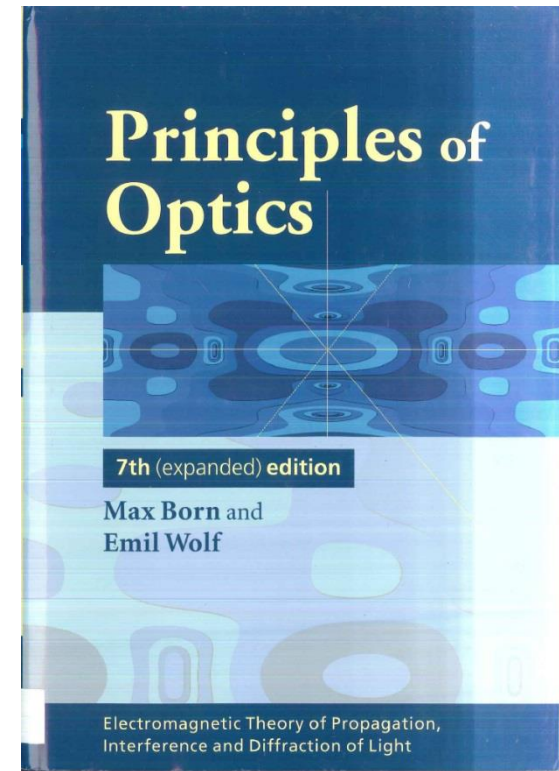
- For more details...



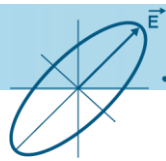
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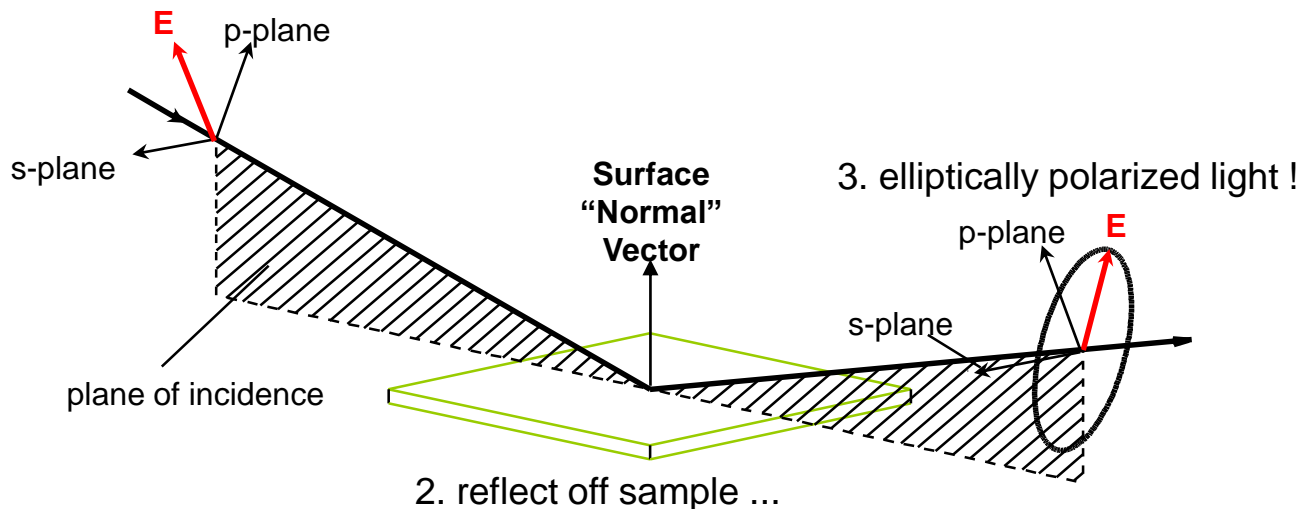


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Ellipsometry: Angle & Plane of Incidence

1. linearly polarized light ...



1. Angle of Incidence.

Measured from Sample Normal.

2. Plane of Incidence.

Defined by incident beam, reflected beam, and sample normal.

3. Polarization Components

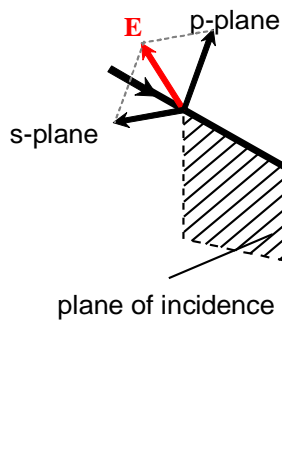
p- and s- are parallel and perpendicular to plane of incidence.

Ellipsometry Measurement

- Measures change in polarization of reflected light.

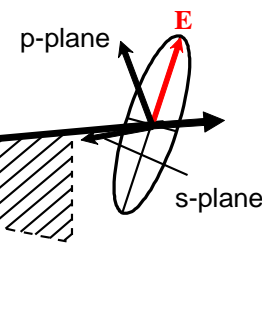
1

$$\tan \psi^{in} e^{i\delta^{in}} = \frac{|E_p^{in}|}{|E_s^{in}|} e^{i(\delta_p^{in} - \delta_s^{in})}$$



2

$$\tan \psi^{out} e^{i\delta^{out}} = \frac{|E_p^{out}|}{|E_s^{out}|} e^{i(\delta_p^{out} - \delta_s^{out})}$$



Change in Polarization represented as Ratio of Light-Out to Light-In

3

$$\rho \equiv \frac{\frac{|E_p^{out}|}{|E_s^{out}|} e^{i(\delta_p^{out} - \delta_s^{out})}}{\frac{|E_p^{in}|}{|E_s^{in}|} e^{i(\delta_p^{in} - \delta_s^{in})}} = \frac{|E_p^{out}|}{|E_s^{out}|} \frac{|E_s^{in}|}{|E_p^{in}|} e^{i(\delta_p^{out} - \delta_s^{out} - \delta_p^{in} + \delta_s^{in})}$$

Ellipsometry Equation

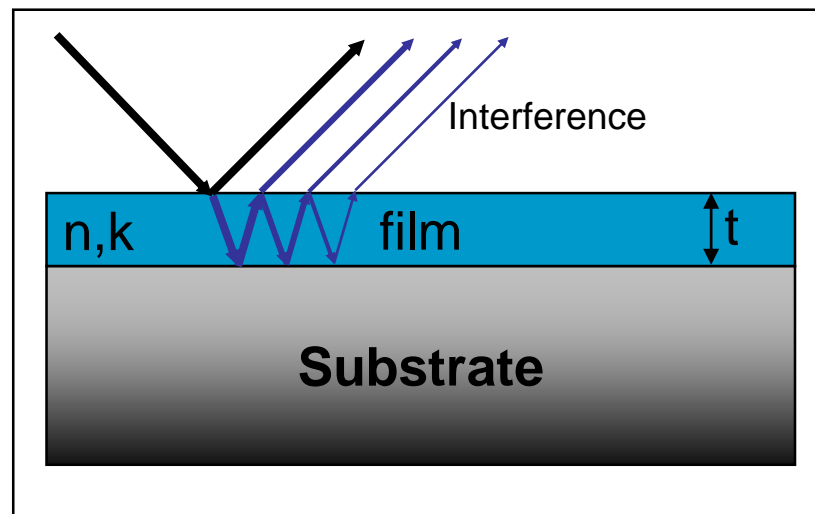
For Reflection, use the following Definitions:

$$r_p = \frac{|E_p^{out}|}{|E_p^{in}|}$$

$$\Delta_p = \delta_p^{refl} - \delta_p^{in}$$

$$r_s = \frac{|E_s^{out}|}{|E_s^{in}|}$$

$$\Delta_s = \delta_s^{refl} - \delta_s^{in}$$



Rewriting, we get the Ellipsometry Equation:

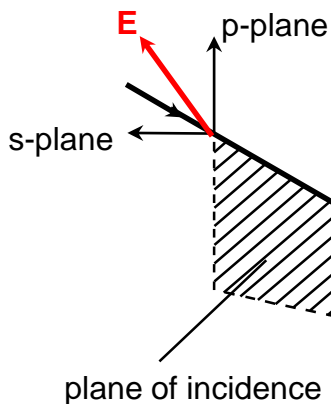
$$\rho = \frac{r_p}{r_s} e^{i(\Delta_p - \Delta_s)} = \tan(\Psi) e^{i\Delta} = \frac{\tilde{r}_p}{\tilde{r}_s}$$

➤ Can determine
Optical constants &
Film Thickness

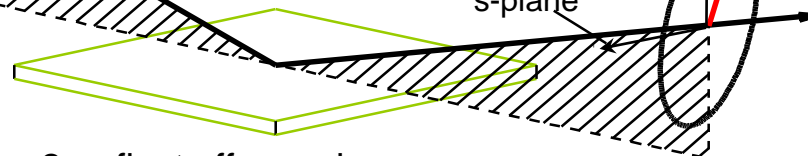
Summary: Ellipsometry Experiment

- Light is reflected from a surface of interest.
- The polarization state of incident light is known.
- The polarization state of reflected/transmitted light is measured.
- An ellipsometer determines the change in polarization from the sample. Ψ and Δ values.

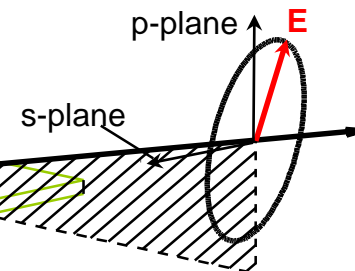
1. linearly polarized light ...



2. reflect off sample ...

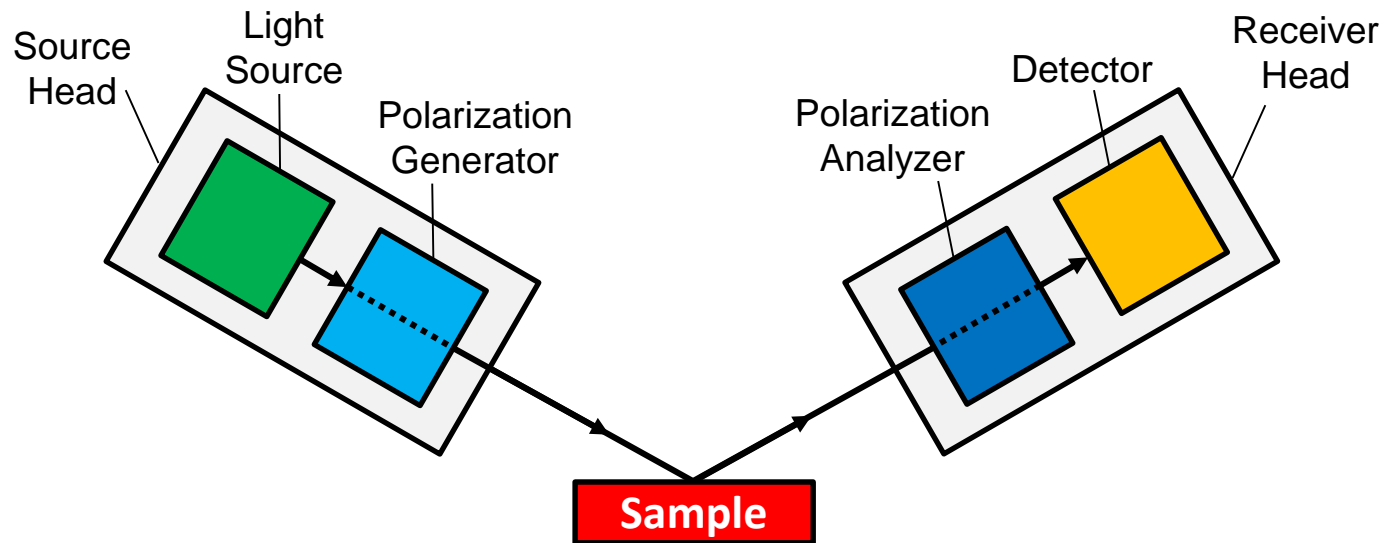


3. elliptically polarized light!



Ellipsometer: Block Diagram

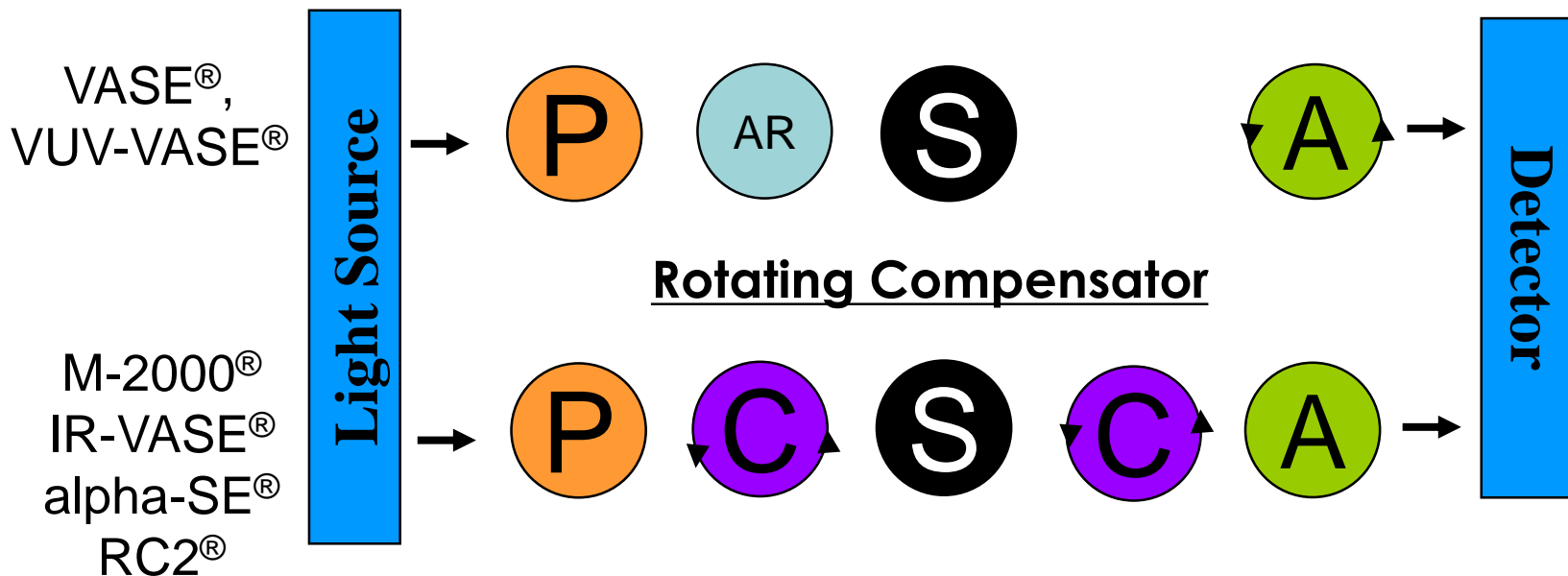
- Every Ellipsometer contains the following components



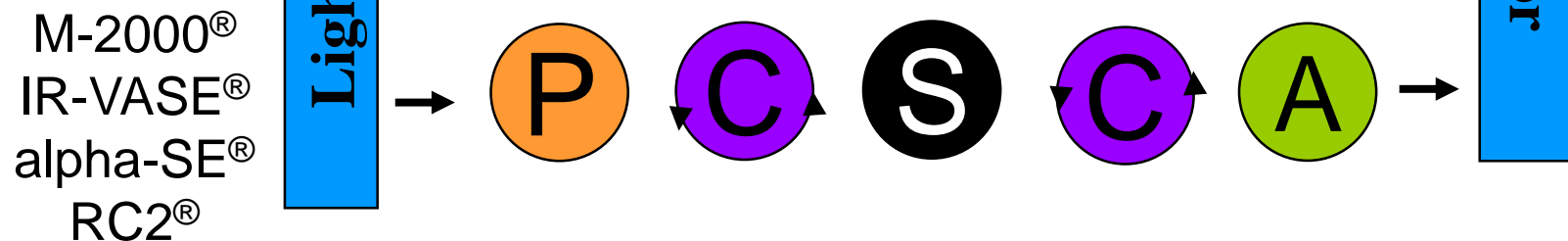
- SE also needs wavelength selection.

Woollam Ellipsometers: Configurations

Rotating Analyzer



Rotating Compensator



Polarizer
AutoRetarder
Compensator
Sample
Compensator
Analyzer

General SE References

Beginner:

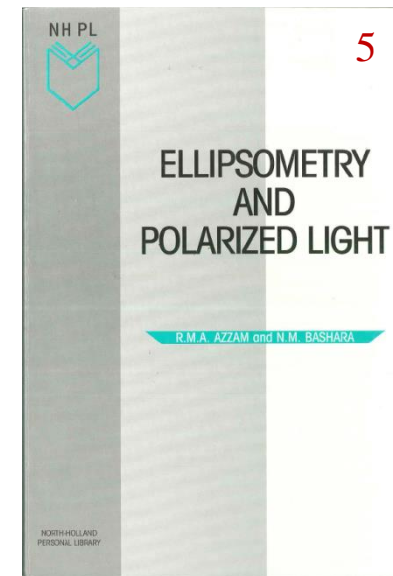
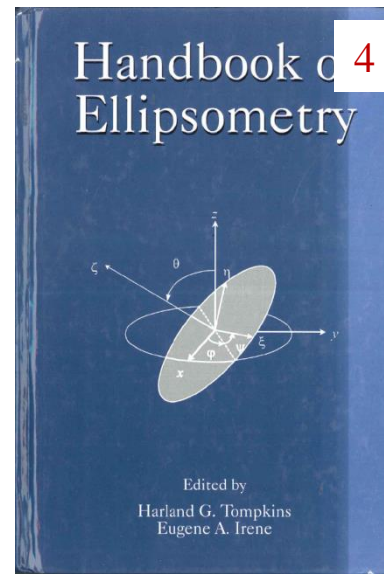
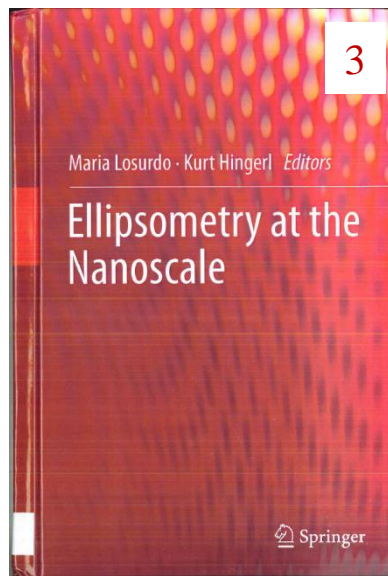
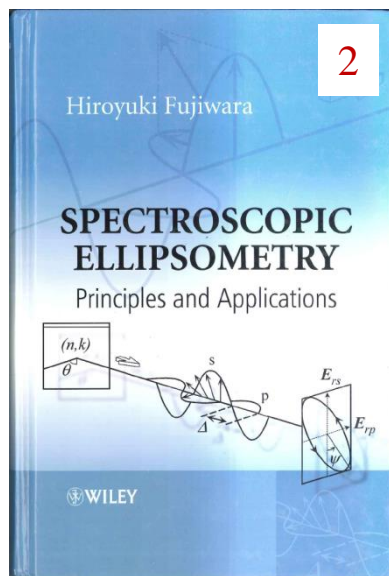
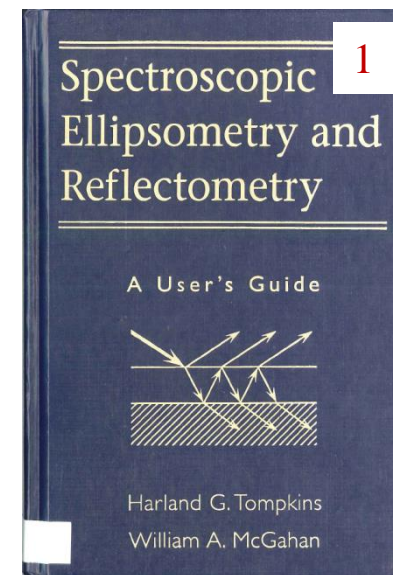
1. H.G. Tompkins, and W.A. McGahan, Spectroscopic Ellipsometry and Reflectometry, John Wiley & Sons, 1999.

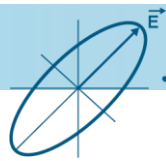
Intermediate:

2. Hiroyuki Fujiwara, Spectroscopic Ellipsometry: Principles and Applications, John Wiley & Sons, 2007.

Advanced:

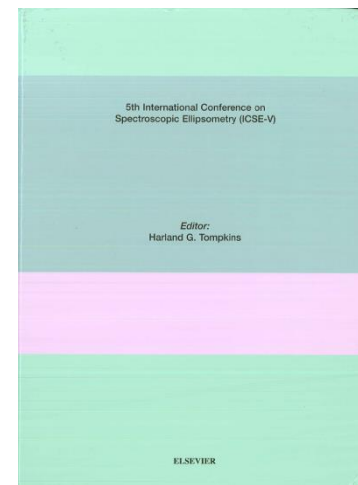
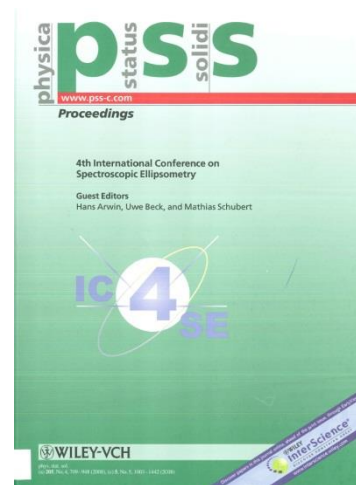
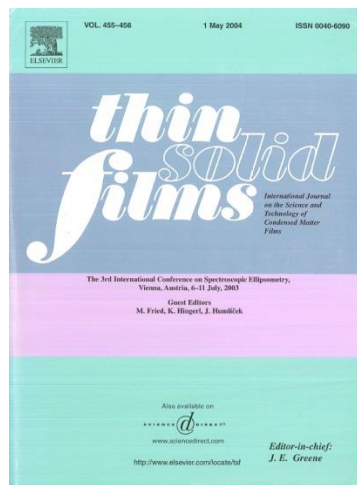
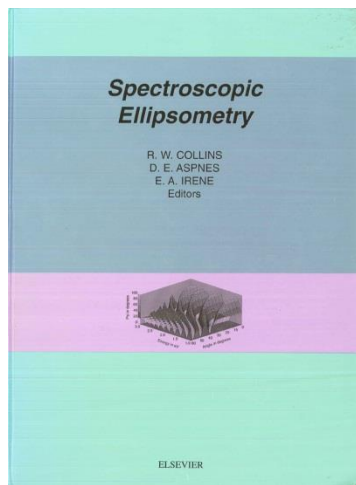
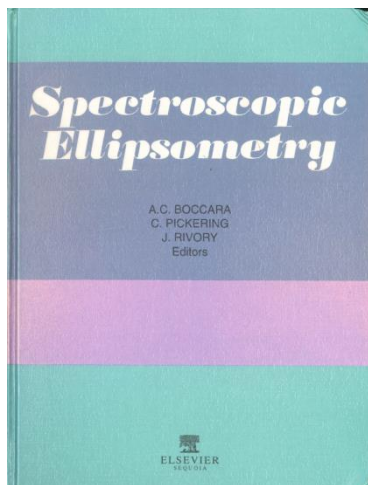
3. Ellipsometry at the Nanoscale, Lasurdo and Hingerl, eds., Springer-Verlag, 2013
4. Handbook of Ellipsometry, Tompkins and Irene, eds., William Andrew Publishing, 2005.
5. R.M.A. Azzam and N.M. Bashara, Ellipsometry and Polarized Light, Elsevier, 1977.





Ellipsometry Conference Proceedings

1. **Spectroscopic Ellipsometry**, (1993) A.C.Boccara, C.Pickering, J.Rivory, Editors, Elsevier Publishing.
2. **Thin Solid Films Vol. 313-314 (1998)**. R.W.Collins, D.E.Aspnes, and E.A. Irene, Editors, Elsevier Science.
3. **Thin Solid Films Vol. 455-456, (2004)**. M. Fried, K. Hingerl, and J. Humlicek, Editors, Elsevier Science.
4. **Phys. Stat. Sol. (c) 5, No. 5, (2008)**. M. Schubert, H. Arwin, U. Beck, Editors, Wiley-VCH.
5. **Thin Solid Films Vol. 519, Issue 9, (2011)**. H. G. Tompkins, Editor, Elsevier Science.



Step 1:

- Select Experimental Data Window.
- Open data file: 2_BK7_SE.dat.
- Append Data 2_BK7_T.dat

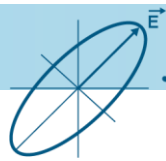
Step 2:

Select Graph Window

- Plot Ψ and Δ data.
- Plot Transmission data.
- What do they mean? (Describe polarization ellipse).
- What is each sensitive to? (Interpret the spectrum).

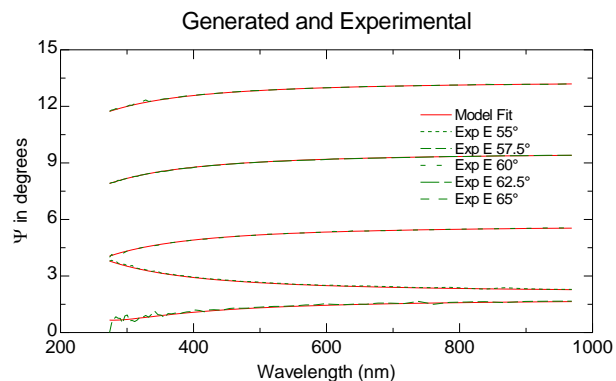
Learning Outcomes:

- Appending different types of data.
- Graphing different data types.
- Sensitivity of different data types to sample properties

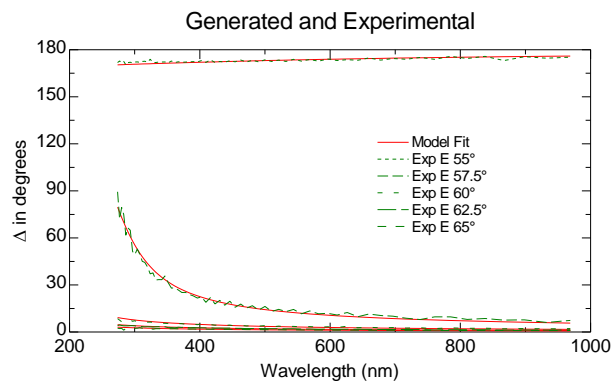


Example 2: Uncoated BK7 Glass Substrate

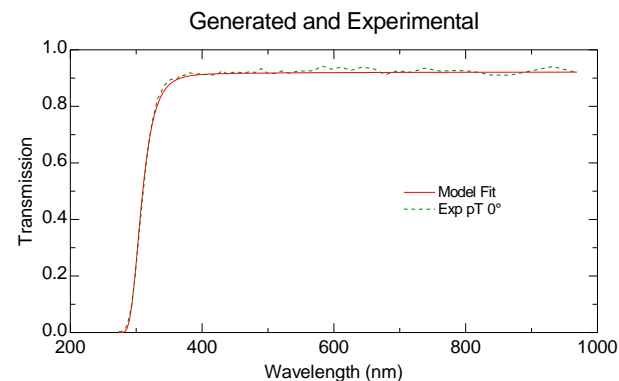
- 3 data types.
- Each sensitive to different sample properties (index, roughness, absorption).



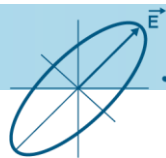
Ψ : index



Δ : Roughness

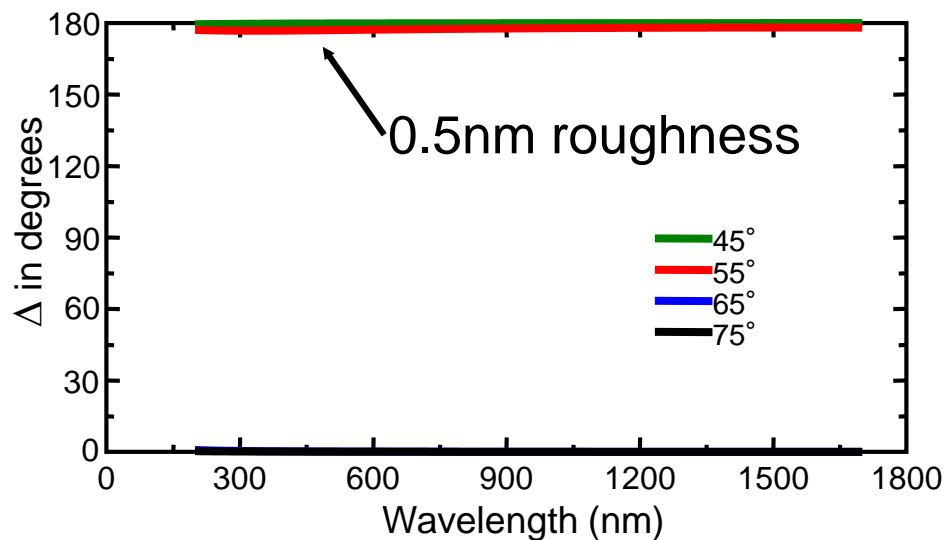
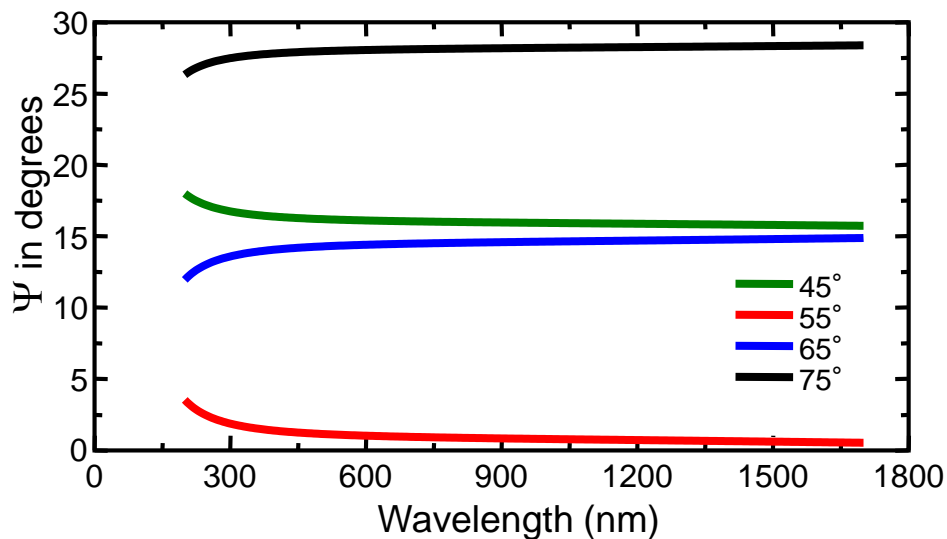


Transmission:
Absorption



Spectral Features: Transparent Substrate

- Psi flat and smooth - follows shape of index
- Delta = 0° or 180° - except for surface films



Step 1:

- Select Experimental Data Window.
- Open data file: 3_Nb.dat.

Step 2:

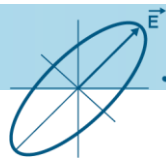
Select Graph Window

- Plot Ψ and Δ data.
- Plot $\langle n \rangle$ & $\langle k \rangle$. NOTE THE $\langle \rangle$ BRACKETS!
- “Pseudo”-values. What do they mean?

Type	Style
	Psi
	Delta
	Tan(Psi)
	Cos(Delta)
	< e1 >
	< e2 >
✓	< n >
	< k >
	Re(rho)
	Im(rho)
	Cos(2*Psi)
	Sin(2*Psi)Cos(Delta)
	Sin(2*Psi)Sin(Delta)
	Transmission
	Reflection
	Absorption
	Transmitted Phase
	Depolarization
	Jones Matrix Quality
	Neutron Reflectivity
	R * K^4

Learning Outcomes:

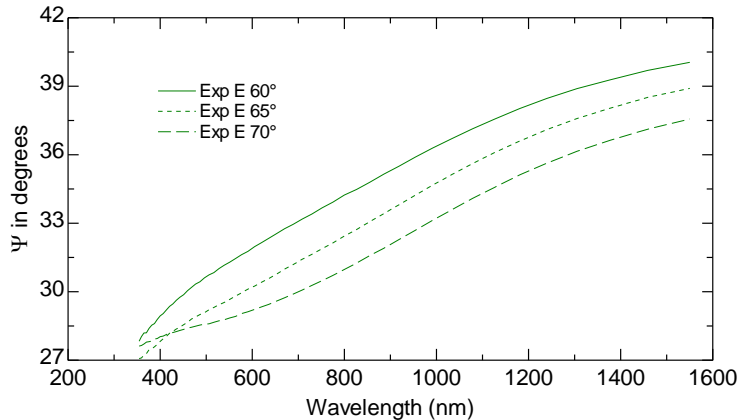
- Study spectrum of opaque material.
- Introduction to “pseudo” $\langle n \rangle$ & $\langle k \rangle$.
- Sample properties causing change in polarization state.



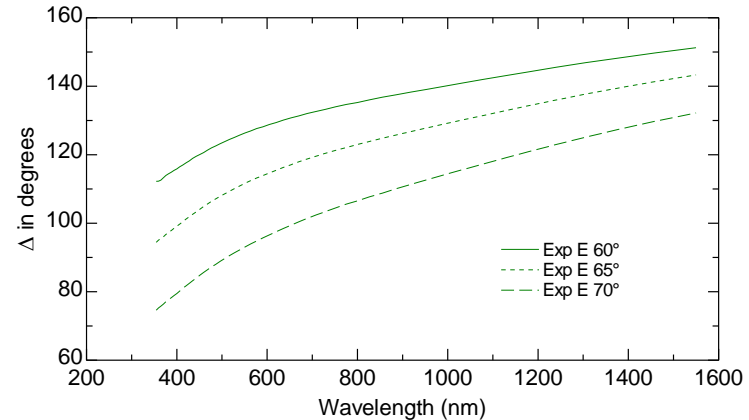
Opaque Sample: Metals

■ Niobium: Psi and Delta

Experimental Data

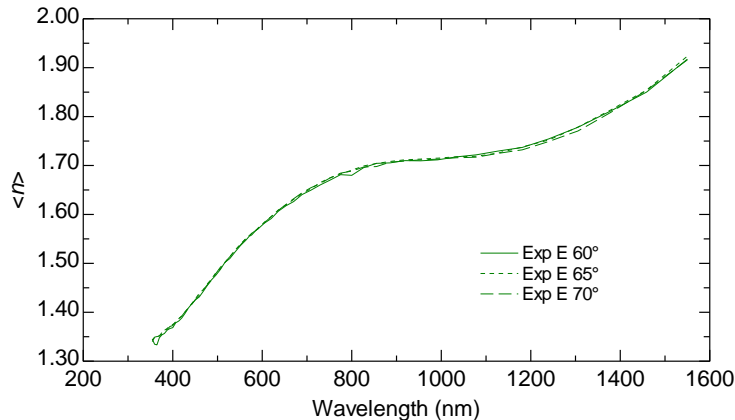


Experimental Data

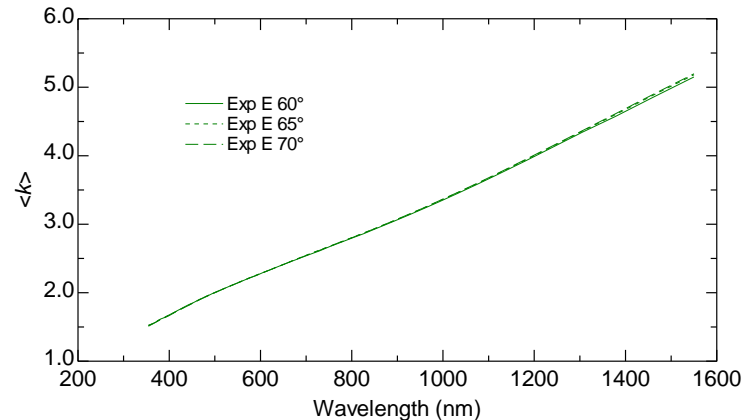


■ Re-plotted as Pseudo $\langle n \rangle$ & $\langle k \rangle$

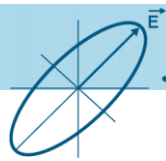
Experimental Data



Experimental Data

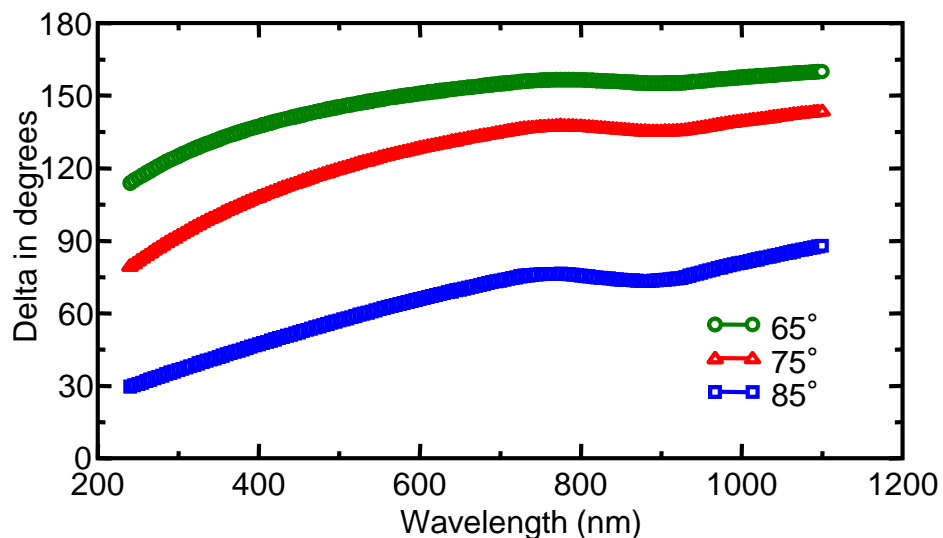
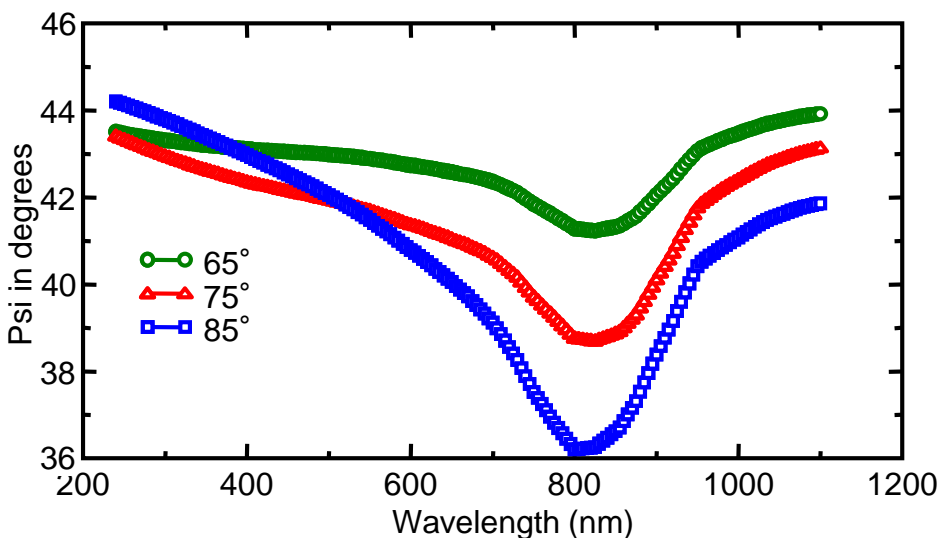


■ Opaque Sample. All $\langle n \rangle$ & $\langle k \rangle$ angles the same.



Spectral Features: Opaque Metals

- Psi stays near 45
- Delta away from 0° or 180°
- Pseudo $\langle n \rangle$ & $\langle k \rangle$ same at all angles.



Substrate Identification

	Transparent	Absorbing
Psi	<ul style="list-style-type: none"> Flat Approaches 0° at Brewster's angle 	<ul style="list-style-type: none"> Shows features of n&k Remains closer to 45° for all angles
Delta	<ul style="list-style-type: none"> Flat Close to 0° or 180°. 	<ul style="list-style-type: none"> Shows features of n&k Stays between 0° and 180°
<Pseudo n&k>	<ul style="list-style-type: none"> <n> has Cauchy shape <k> close to zero 	<ul style="list-style-type: none"> <n&k> follow actual n&k.

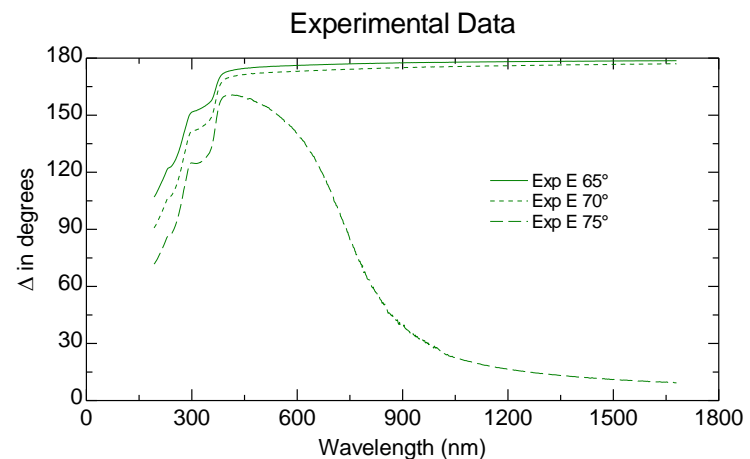
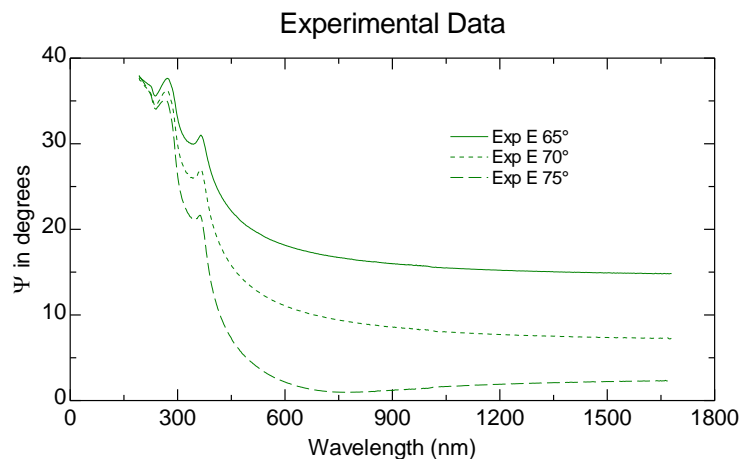
Transparent Substrate Exceptions:

1. <n> separation for variable angle when backside reflections are present.
2. <k> non-zero and Delta away from $0, 180^\circ$ if surface layer (e.g. roughness).

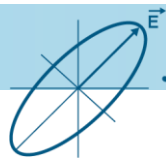
What about Semi-Absorbing?

Step 1:

- Select Experimental Data Window.
- Open data file: 4_Si wafer.dat.

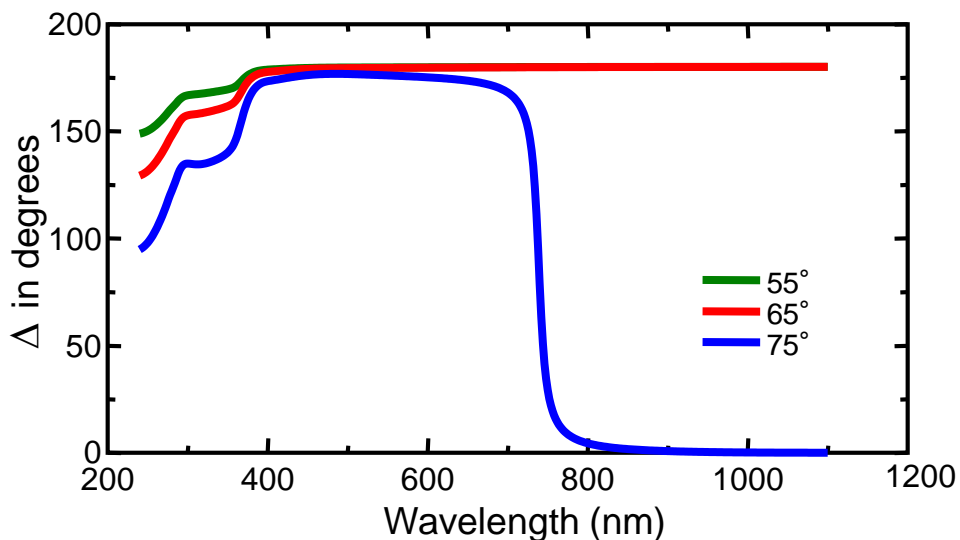
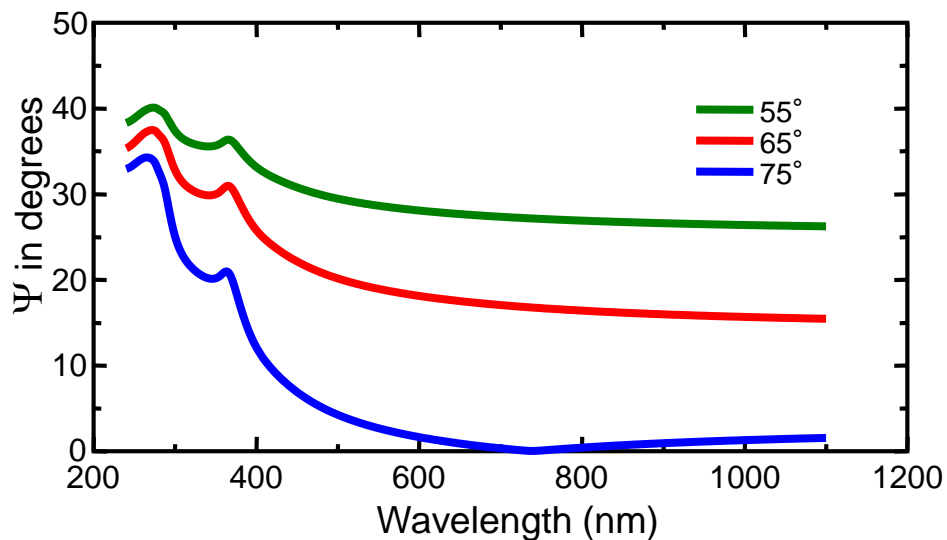
**Learning Outcomes:**

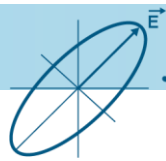
- Study spectrum of crystalline material.
- Note sharp structure below 450 nm. Why? Why so sharp?
- Identify transparent and absorbing regions.



Substrate - Semiconductors

- Psi follows shape of absorption.
- Delta away from 0° or 180° when absorbing.
- Sharp features due to absorption.





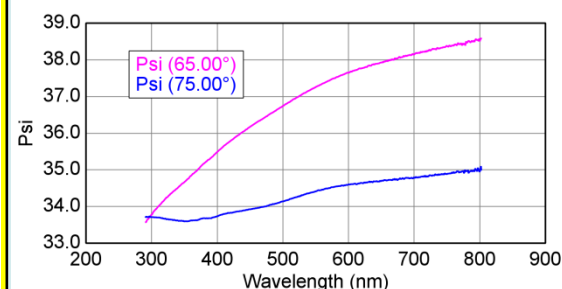
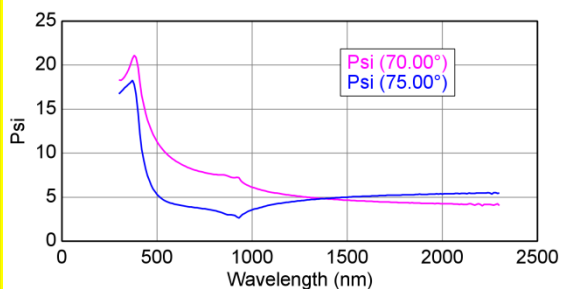
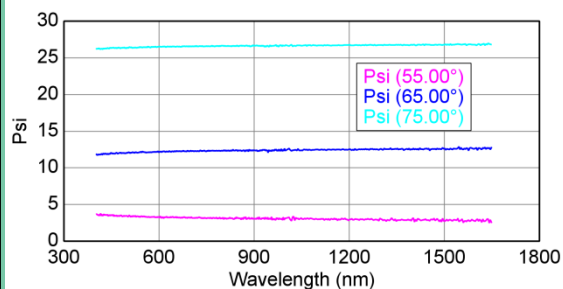
Review: Substrate Types, Spectral Features.

Transparent

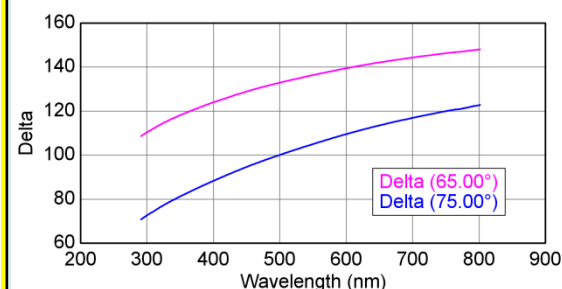
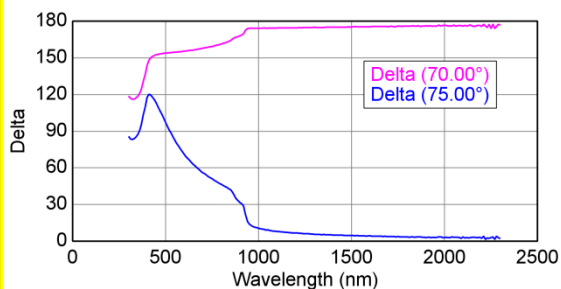
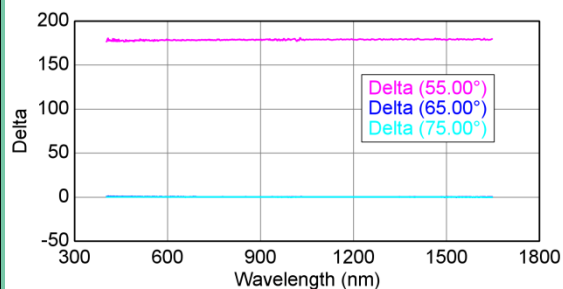
Semi-Absorbing

Absorbing

Ψ



Δ

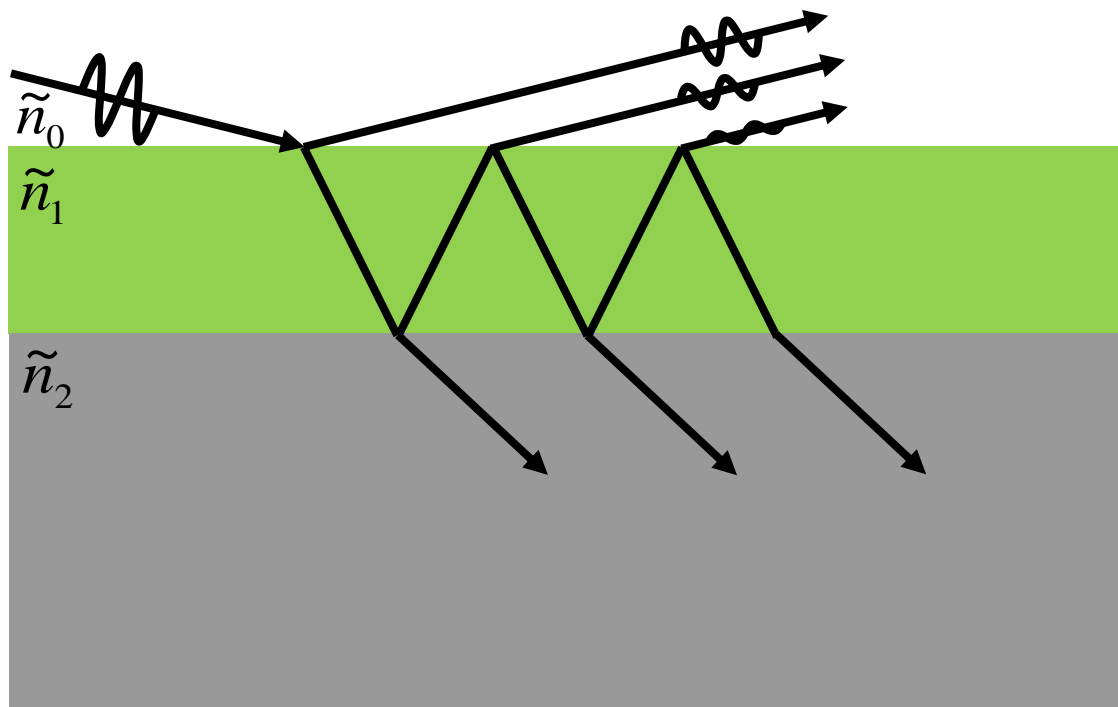


Describe unique features of each spectrum.

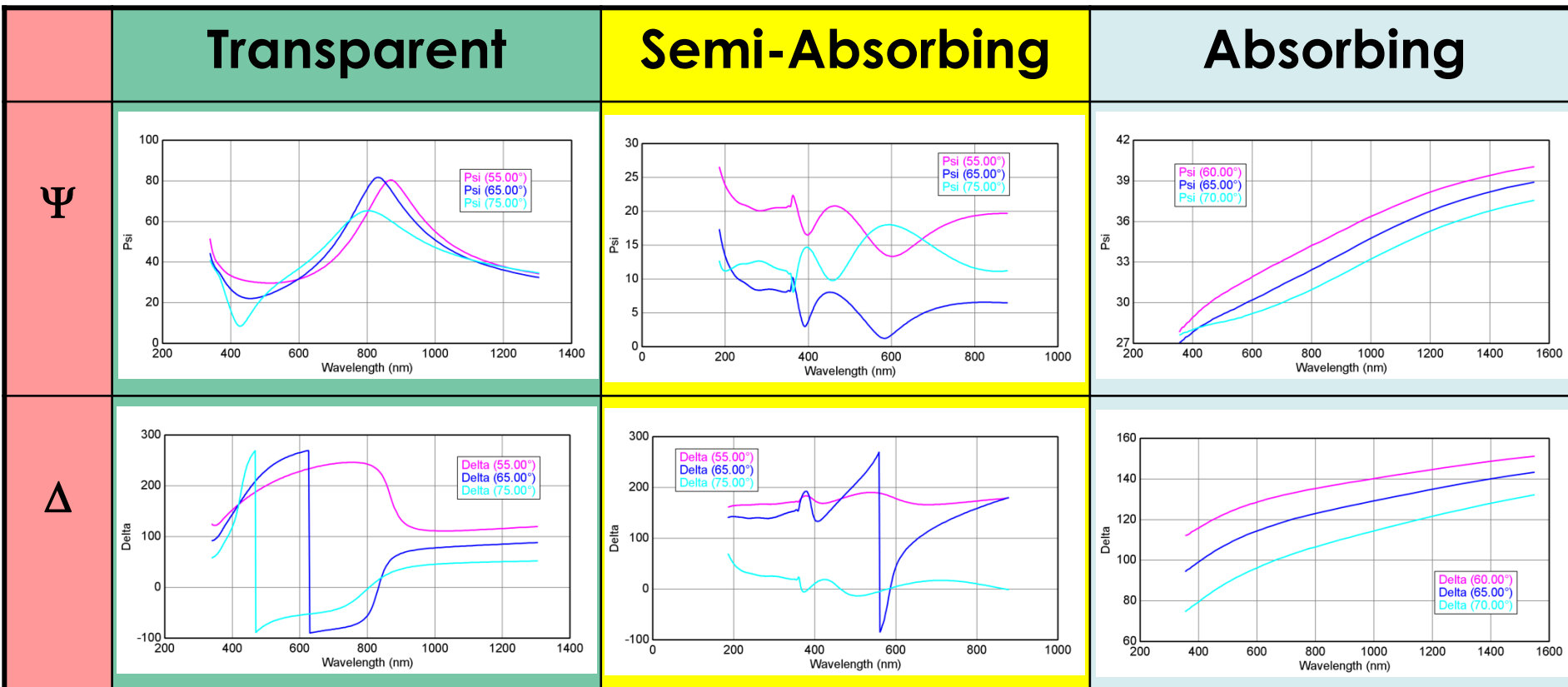
Coated Samples!

Thin Film Identification

- Multiple Reflections at interfaces.
- Use to estimate film thickness and Index.
- Can be transparent, Absorbing, or Semi-Absorbing.



Coated Thin Film Examples



Coatings add interference effects in transparent regions.

Transparent Film on Silicon

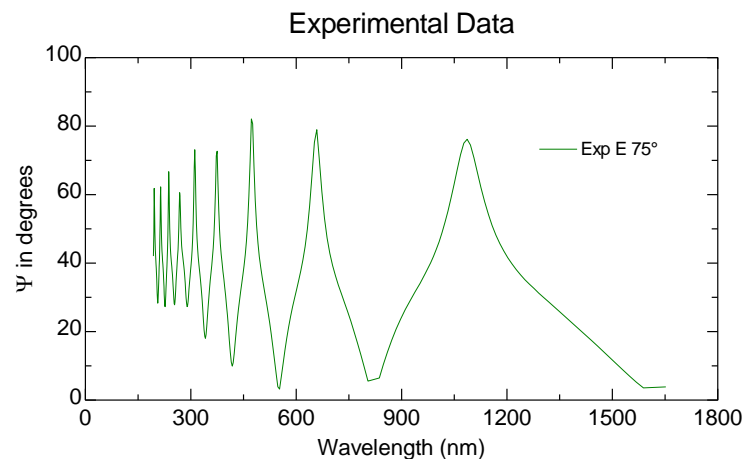
Step 1:

- Open data file: 5_SiO2 on Si.dat.

Step 2:

Select Graph Window

- Plot Ψ and Δ data.
- **Note the interference effects.**
- What Causes these oscillations?

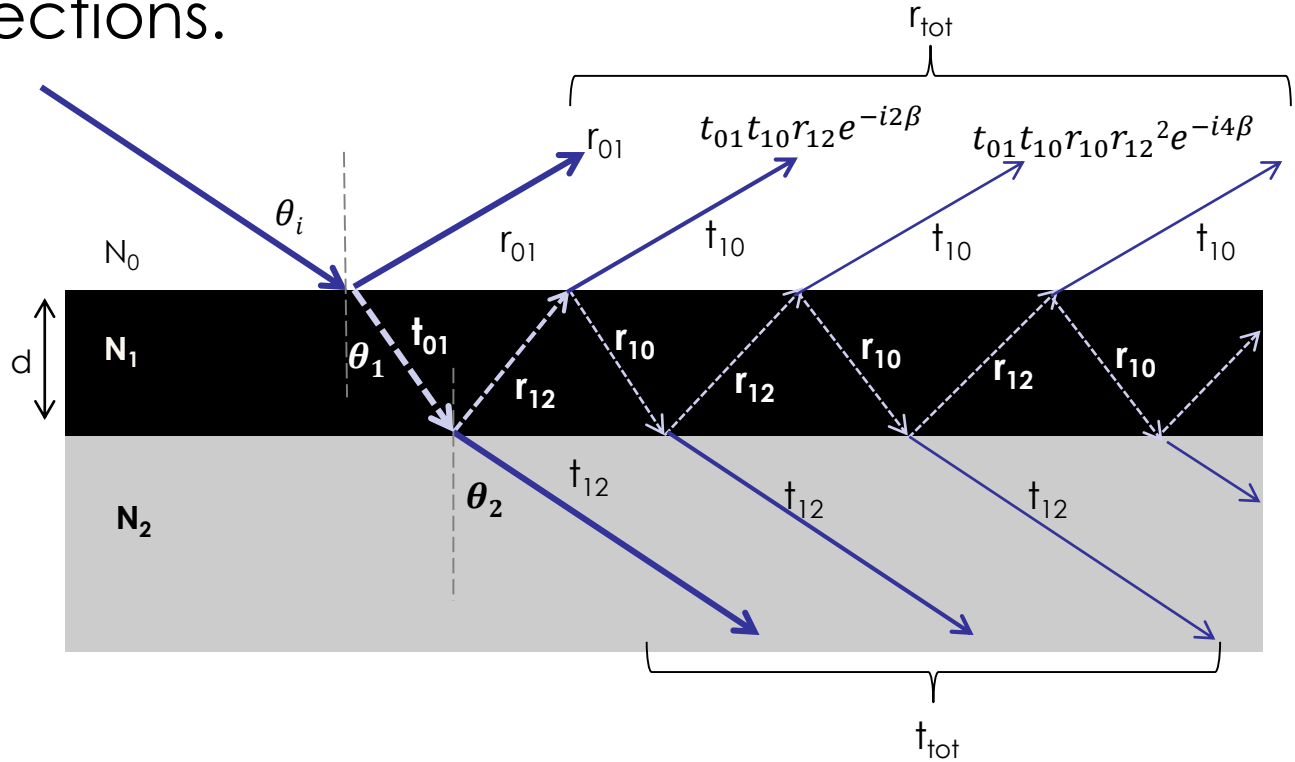


Learning Outcomes:

- Identify spectrum of a coated substrate with transparent film.
- Observe thin-film interference effects from transparent Film.

Thin Film on Substrate

- Multiple reflections in single film lead to an infinite series of reflections.



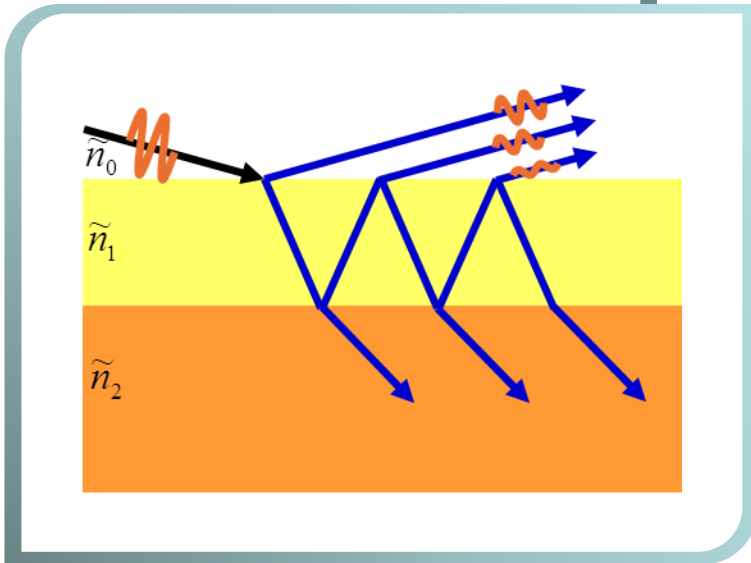
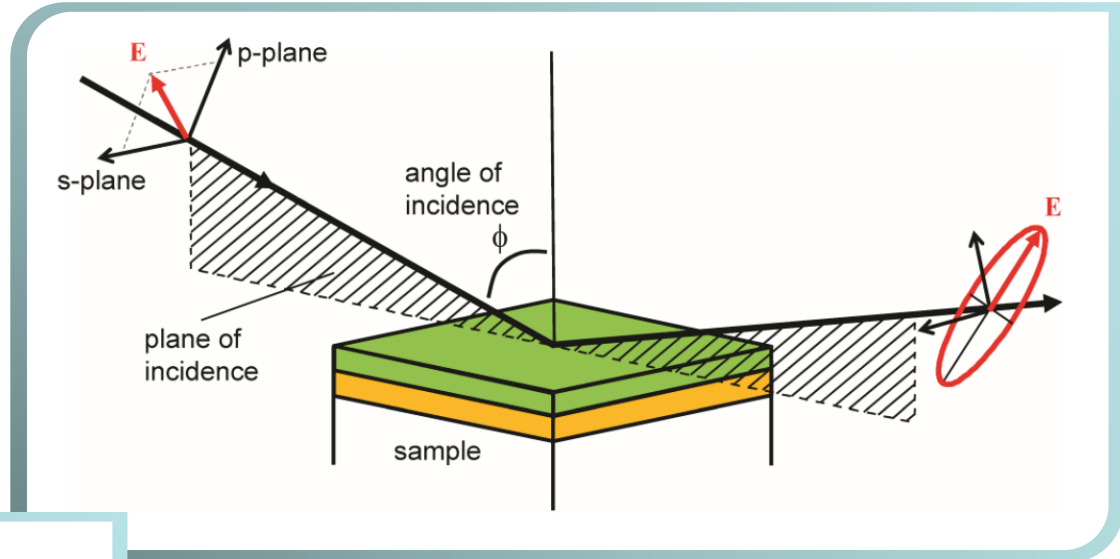
Phase from different optical paths is tracked by film phase thickness (β)

$$\beta = 2\pi \left(\frac{d}{\lambda} \right) N_1 \cos \theta_1$$

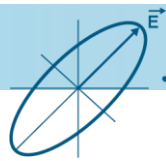
$$r_{tot} = r_{01} + t_{01} r_{12} t_{10} e^{-2i\beta} + t_{01} r_{12}^2 r_{10} t_{10} e^{-4i\beta} + \dots$$

Thin-Film Interference Effects

- SE measures polarization change as light interacts with sample.



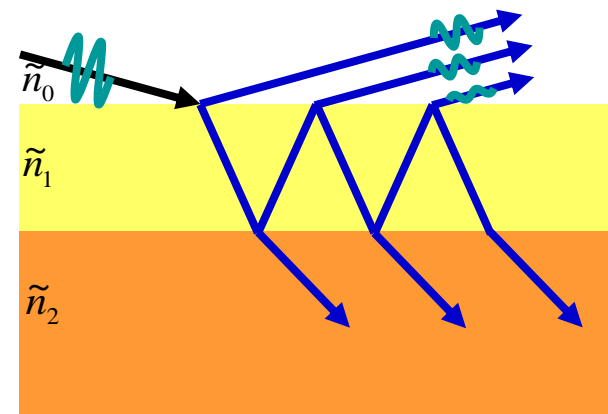
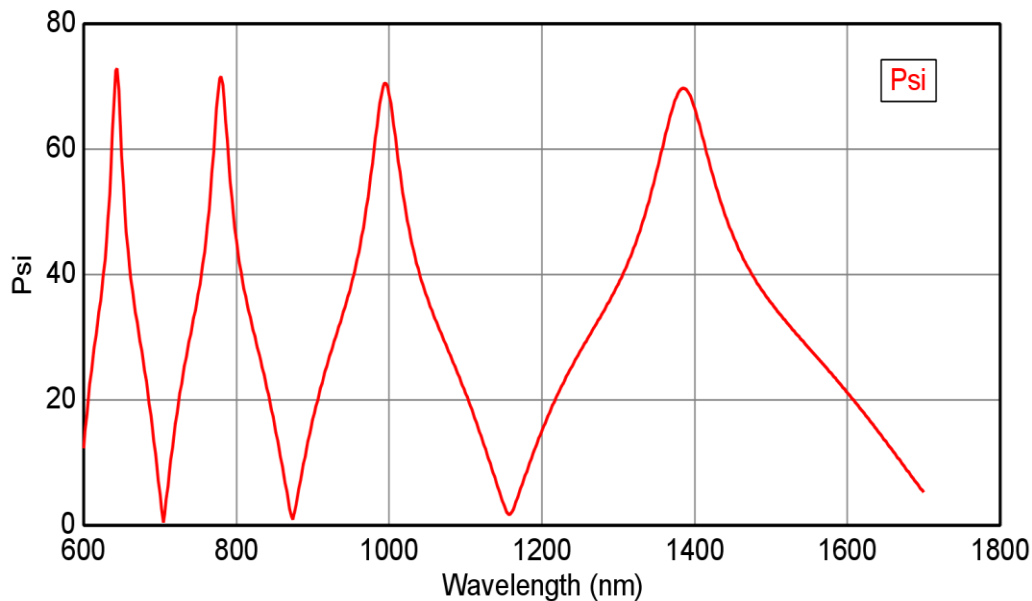
- Interference occurs as light recombines after traveling different paths through thin film.



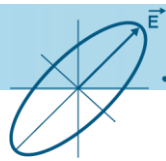
SE features – Transparent Films

- Oscillation patterns in ellipsometry data due to thin film interference.
- Pattern affected by thickness and index.

Spectroscopic Ellipsometric (SE) Data

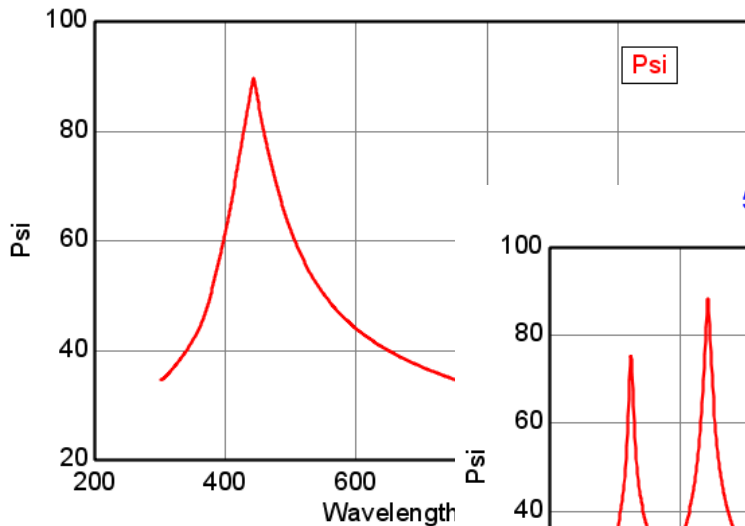


**Transparent -
oscillations**

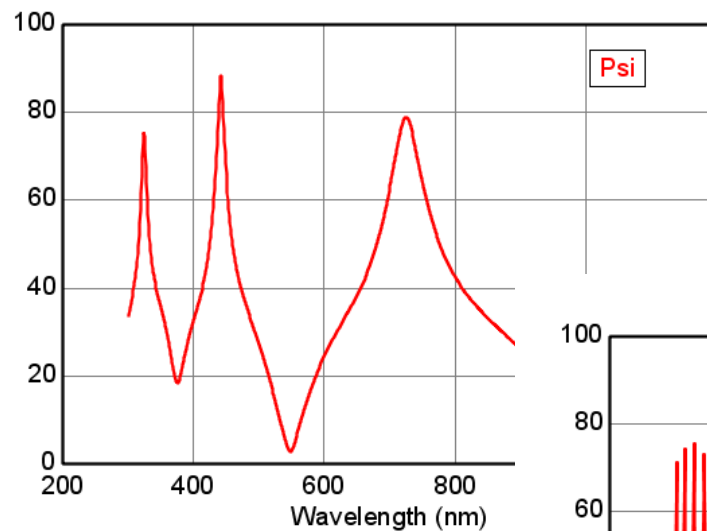


Thickness Effects

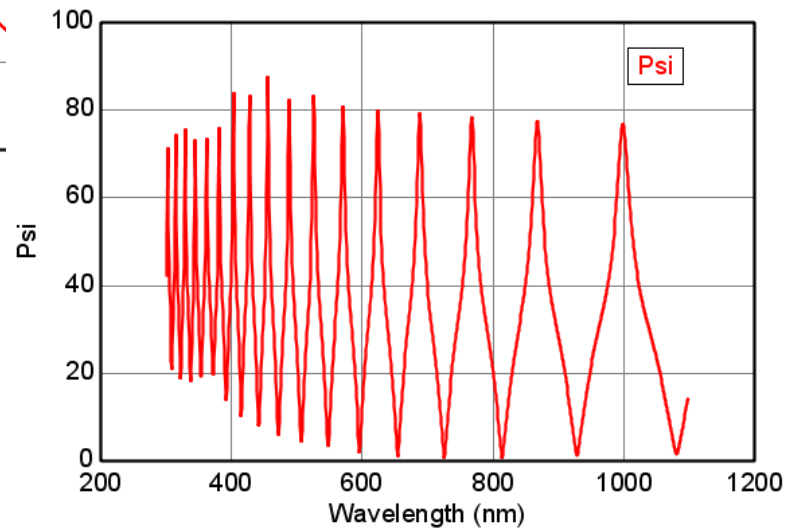
100 nm oxide on Si



500 nm oxide on Si



3 microns oxide on Si



Thicker films have more interference oscillations

Very Thick Transparent Film on Glass

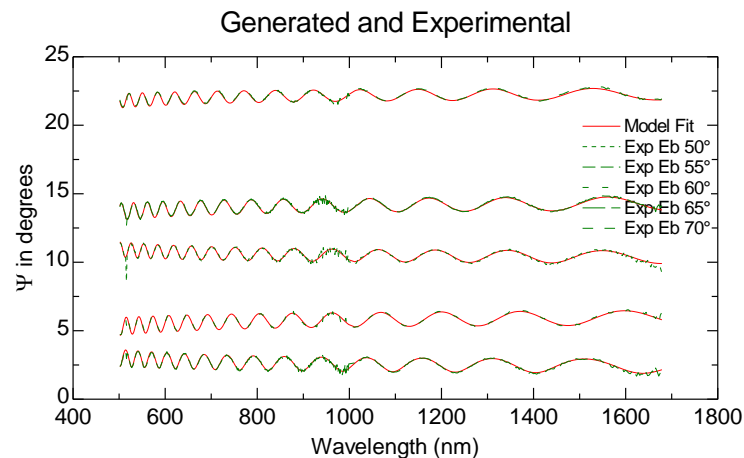
Step 1:

- Open data file: 6_Dielectric on Glass.dat.

Step 2:

Select Graph Window

- Plot Ψ and Δ data.
- Thick or thin film?
- Why small amplitudes?



Learning Outcomes:

- Identify spectrum of thick versus thin transparent film.
- Note small amplitude of oscillations. Why?

Thin Film Identification

	Transparent	Absorbing
Psi	<ul style="list-style-type: none"> ▪ Oscillates ▪ Size of oscillations signify index difference between substrate and thin film ▪ Number of oscillations indicate thickness 	<ul style="list-style-type: none"> ▪ No oscillations. ▪ Shows features of n&k. ▪ Looks like opaque substrate.
Delta	<ul style="list-style-type: none"> ▪ Oscillates ▪ Number of oscillations indicate thickness 	<ul style="list-style-type: none"> ▪ Shows features of n&k. ▪ Stays between 0° and 180°.
<Pseudo n&k>	<ul style="list-style-type: none"> ▪ May separate for multi-angles. 	<ul style="list-style-type: none"> ▪ Overlapping at multi-angles.

VERY THIN LAYER Exceptions:

1. Oscillations will not appear until about 25-50 nm thickness.
2. Psi may go above 45° for thin coatings.

What about Semi-Absorbing?

Break!



Semi-Absorbing Film on Silicon

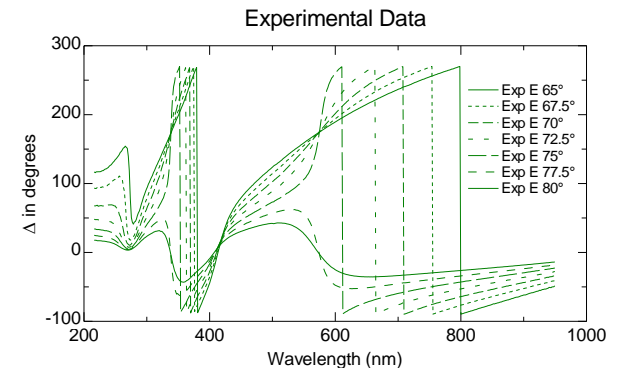
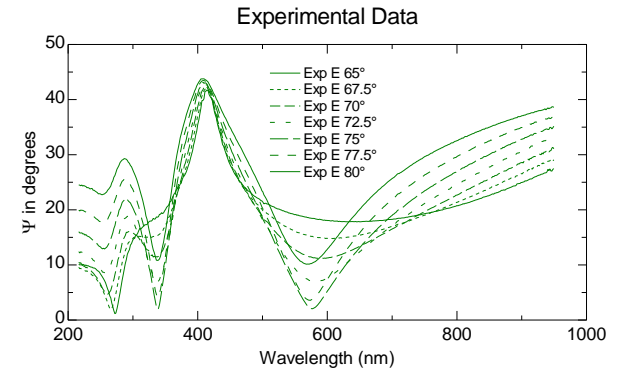
Step 1:

- Open data file: 7_SiNx on Si.dat.

Step 2:

Select Graph Window

- Plot Ψ and Δ data.
- Note the interference effects.
- **Discuss IR and UV behavior.**



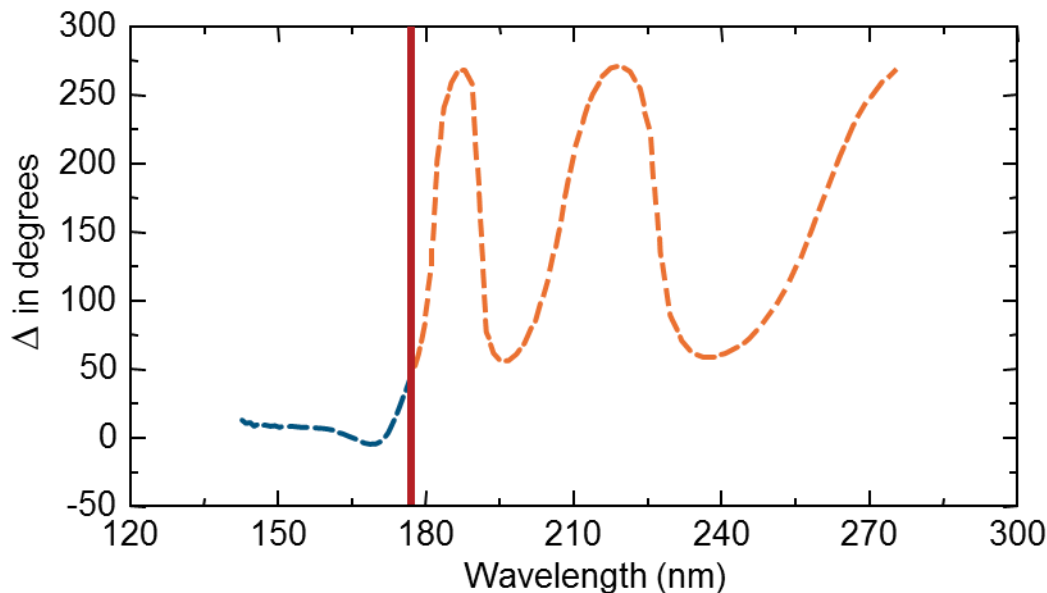
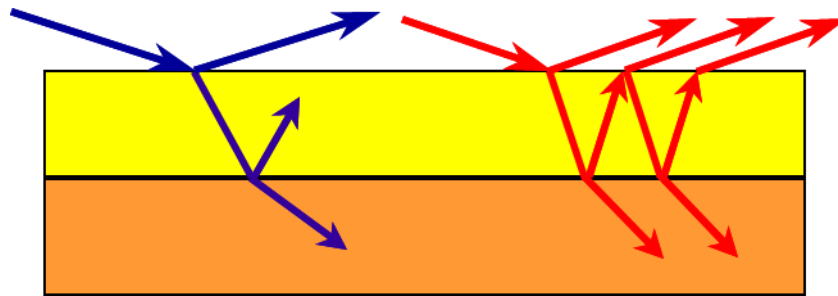
Learning Outcomes:

- Identify spectrum of a UV absorbing film.
- Observe thin-film interference effects and absorption effects.

Semi-Absorbing Films

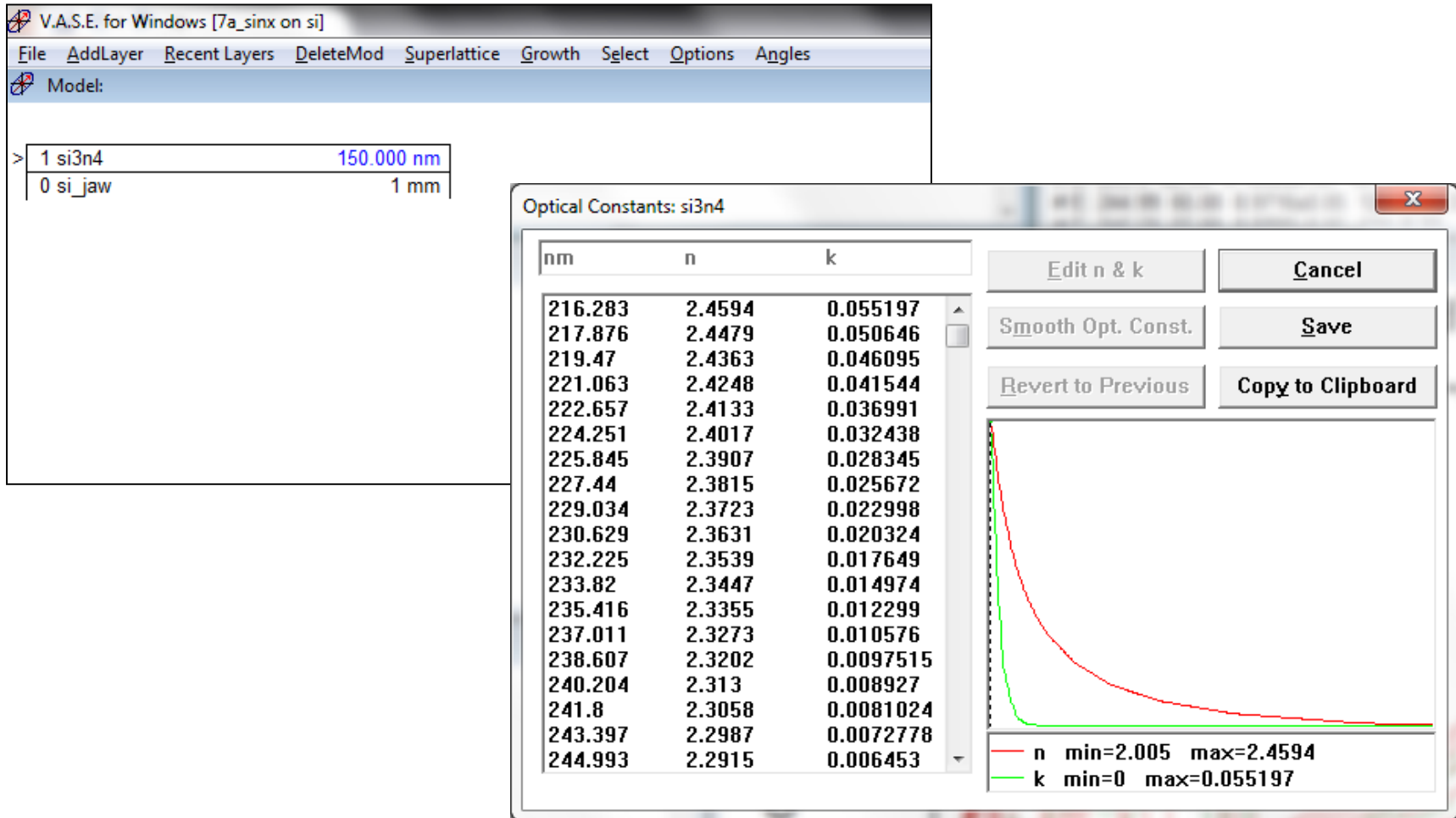
Spectral Identification: What to expect?

- If light is absorbed before returning to surface, only top reflection is 'seen' (Film appears as opaque substrate).



WVASE Model Window

Add layers. Define fit parameters.



The screenshot shows the V.A.S.E. for Windows software interface. The main window displays a model with two layers: a 150.000 nm layer of Si_3N_4 and a 1 mm layer of Si . An 'Optical Constants: Si_3N_4 ' dialog box is open, showing a table of refractive index (n) and extinction coefficient (k) values for the Si_3N_4 layer across a range of wavelengths from 216.283 nm to 244.993 nm. A graph on the right side of the dialog box plots n (red line) and k (green line) against wavelength, showing n decreasing from approximately 2.45 to 2.0 and k remaining near zero.

nm	n	k
216.283	2.4594	0.055197
217.876	2.4479	0.050646
219.47	2.4363	0.046095
221.063	2.4248	0.041544
222.657	2.4133	0.036991
224.251	2.4017	0.032438
225.845	2.3907	0.028345
227.44	2.3815	0.025672
229.034	2.3723	0.022998
230.629	2.3631	0.020324
232.225	2.3539	0.017649
233.82	2.3447	0.014974
235.416	2.3355	0.012299
237.011	2.3273	0.010576
238.607	2.3202	0.0097515
240.204	2.313	0.008927
241.8	2.3058	0.0081024
243.397	2.2987	0.0072778
244.993	2.2915	0.006453

Contains optical constants of each layer.
What are “Optical Constants”?

Build Model For Silicon Nitride on Silicon

Step 1:

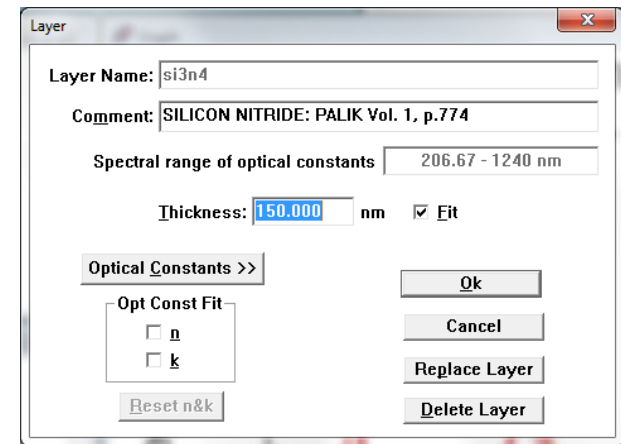
- Open data file: 7_SiNx on Si.dat.

1	si3n4	150.000 nm
0	si_jaw	1 mm

Step 2:

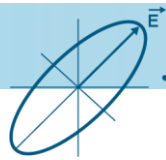
Select Model Window.

- Add Layer: Si_jaw.mat.
- Add Layer: Si3N4.mat.
- Add fit Parameter: Film Thickness.
- Show table of optical constants.



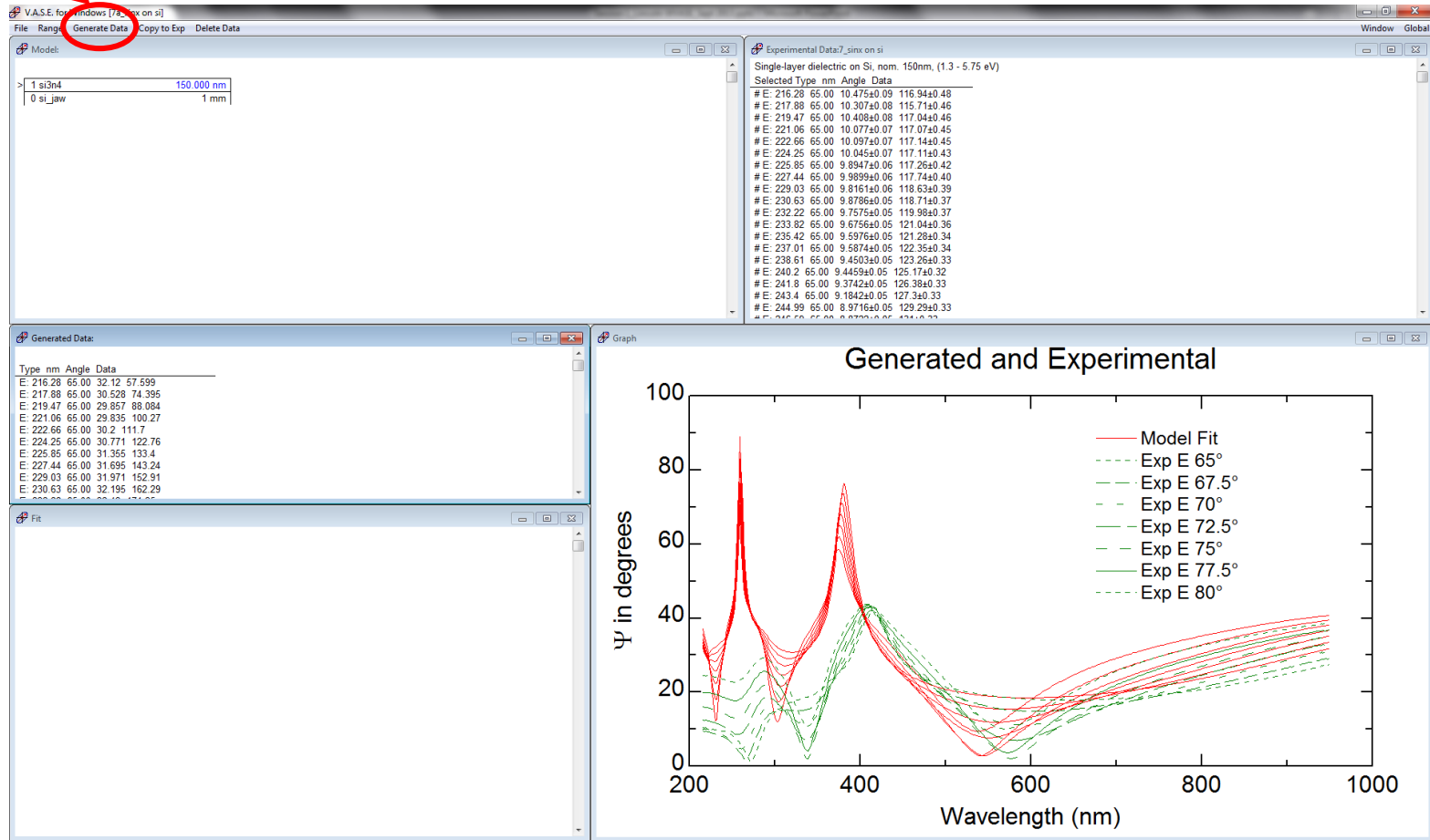
Learning Outcomes:

- Building a model. Adding layers.
- Adding fit parameters.



Generate Data Window

Generates data from the Model



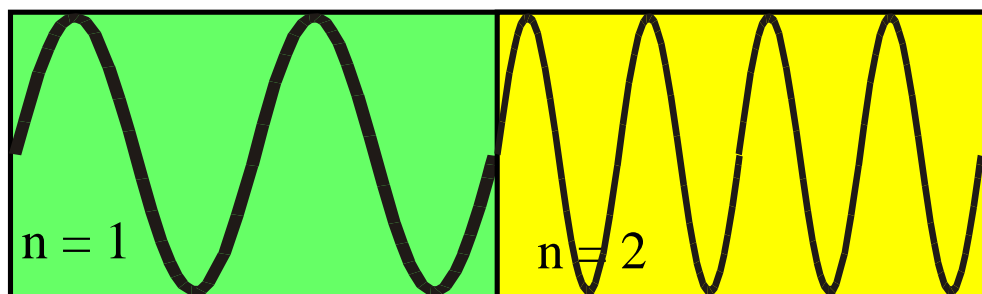
Graphs compare Model Generated and Experimental Data.

Thickness is close, so why not a perfect match?

Optical Constants, Refractive Index, n

Light in Different Media:

Velocity and wavelength vary in different materials.



$$v = \frac{c}{n}$$

speed of light

Frequency (color) of wave remains the same! $f = \frac{v}{\lambda}$

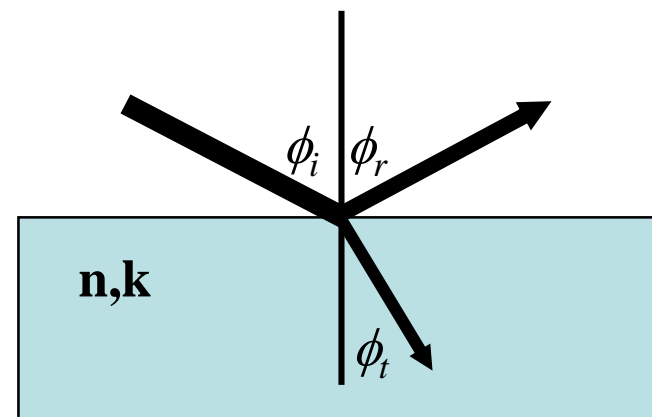
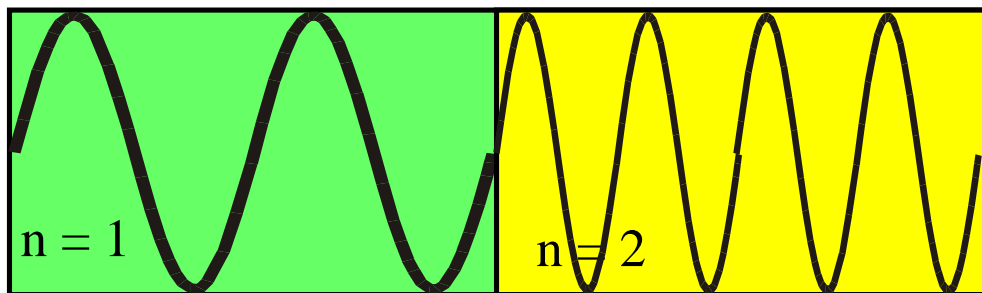
Energy of photon remains the same:

$$E(eV) = h\nu \cong \frac{1,240}{\lambda(nm)}$$

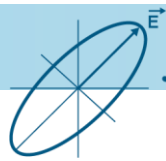
Planck's constant

Index of Refraction, n

- **Index of Refraction (n)**
- **Describes How Light is affected by Materials:**
reflection, refraction, phase velocity, absorption



$$\begin{array}{l}
 \nearrow \\
 \text{Frequency constant}
 \end{array}
 \nu = \frac{v}{\lambda} = \frac{c}{n\lambda}$$



Refractive Index, n

- Determines **Wave speed**.

$$v = c/n$$

- Determines **Angle of Propagation**.

- Snell's Law of Refraction:

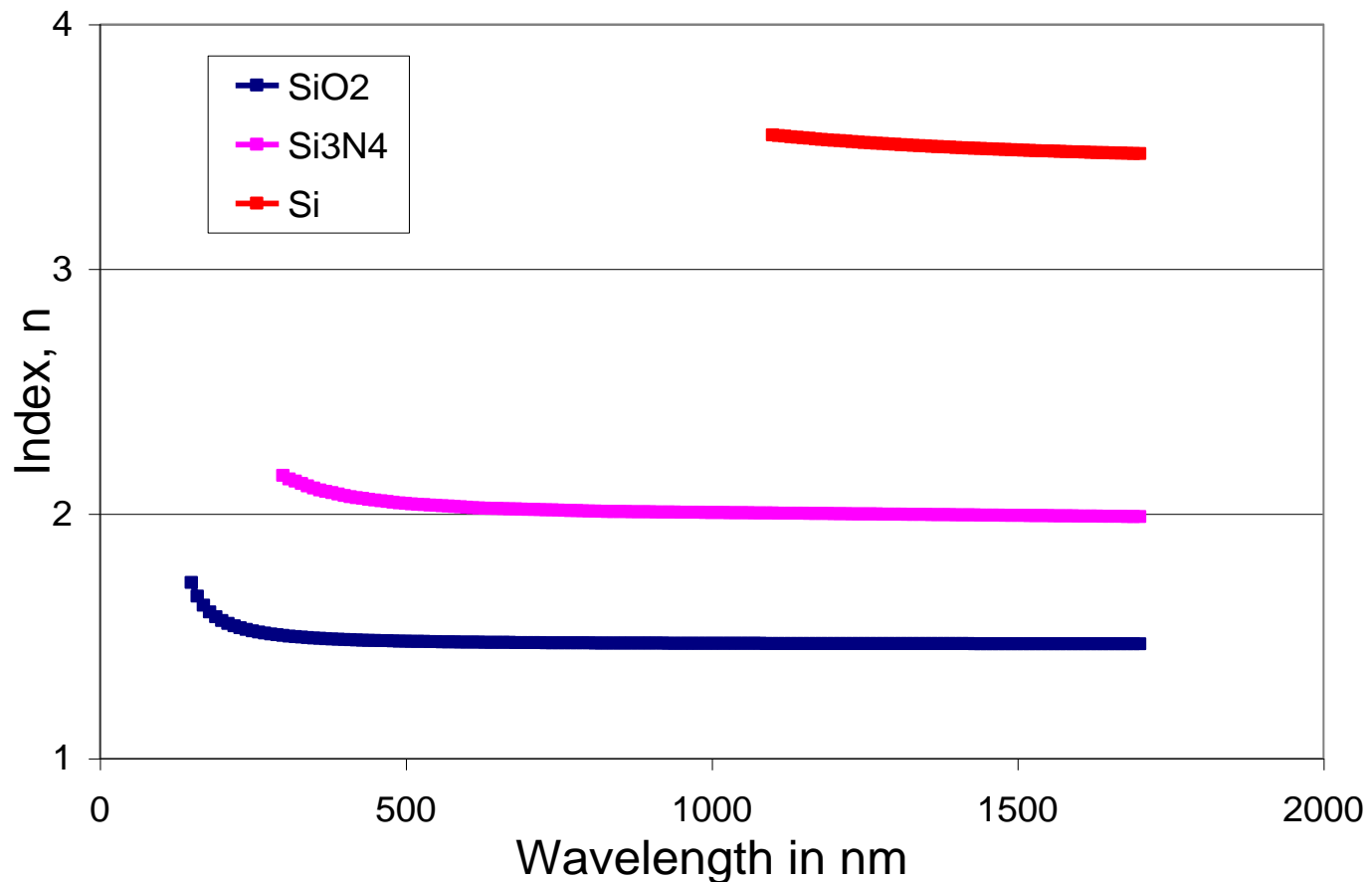
$$n_1 \sin \theta_1 = n_2 \sin \theta_2$$

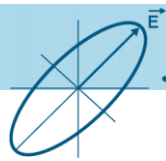
- Example: Pencil in glass of water appears “Bent”, or “Broken”. Caused by refraction.



Refractive Index: Transparent Materials

- Index decreases for longer wavelengths.
- Higher index for stronger UV absorption.





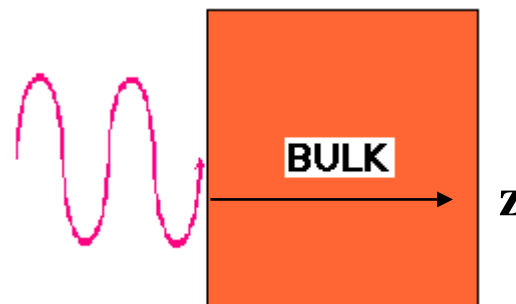
Absorption and Extinction

$$I = I_0 e^{-\alpha z}$$

$$\alpha = \frac{4\pi k}{\lambda}$$

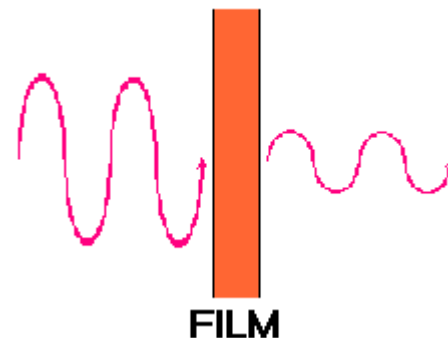
Bulk Material Absorption:

- Deeper propagation gives:
- = more energy loss.
- = complete extinction.



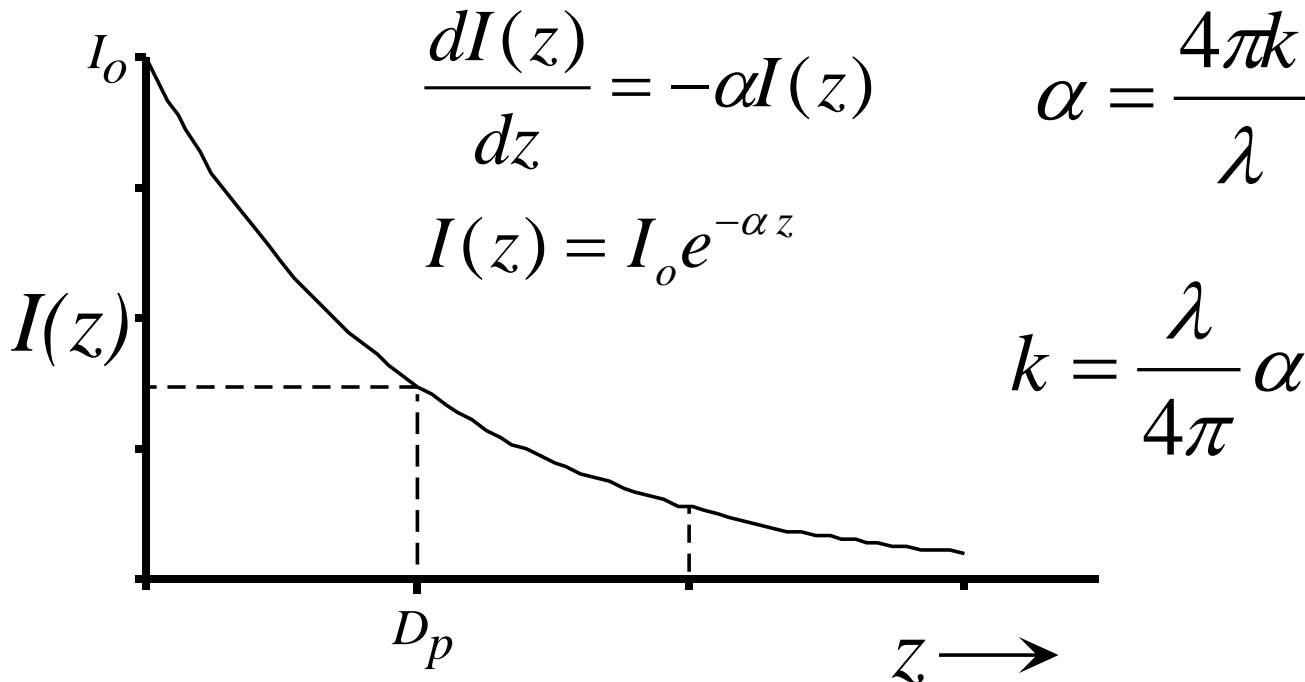
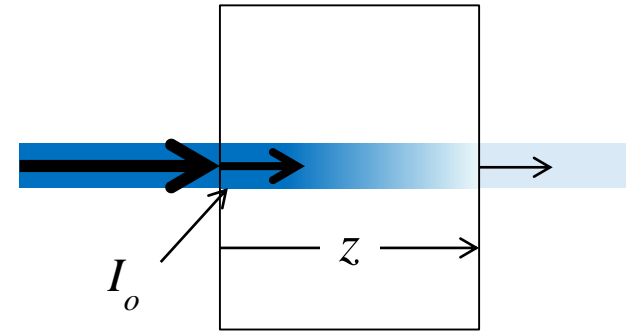
Absorbing films:

- Increasing thickness gives:
- = longer propagation path in film.
- = wave spends longer time in film.
- = more absorption by material.
- = more extinction of wave.



Absorption: Beer-Lambert-Bouguer Law

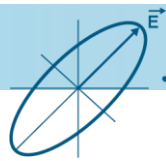
- Absorption coefficient (α)
- Extinction coefficient (k)
 - Loss of wave energy to the material.



Pierre Bouguer
(1698-1758)



Johann Heinrich Lambert
(1728-1777)

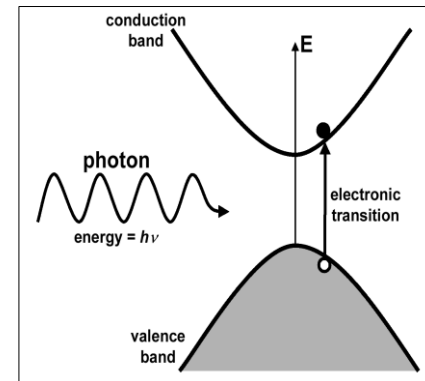


Multiple types of optical absorption

- Common absorption of EM waves:

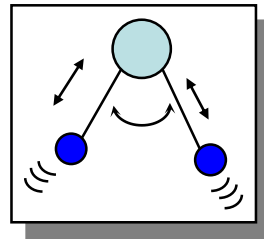
Electronic

UV-visible-near IR frequencies



Vibrational

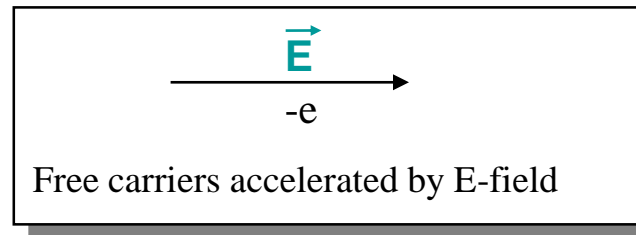
mid-IR freq



Free carriers

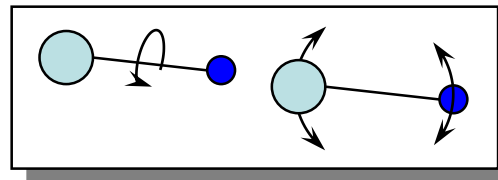
(conductivity)

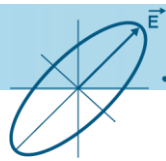
mostly IR



Rotational

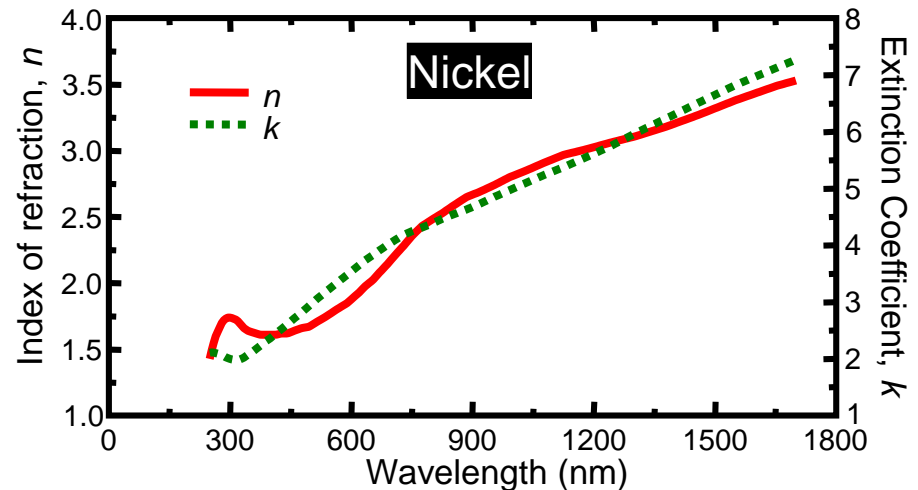
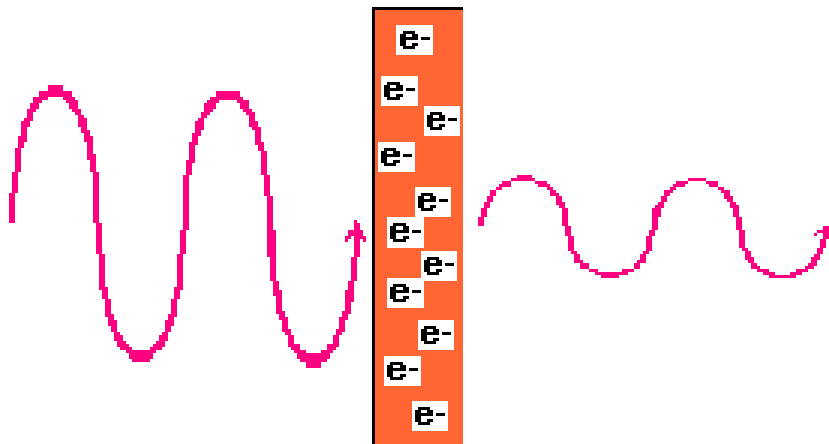
(microwave oven)





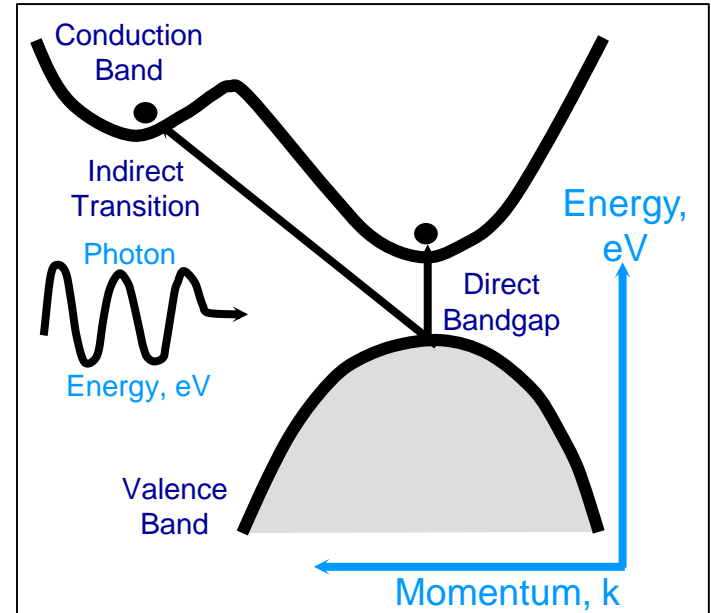
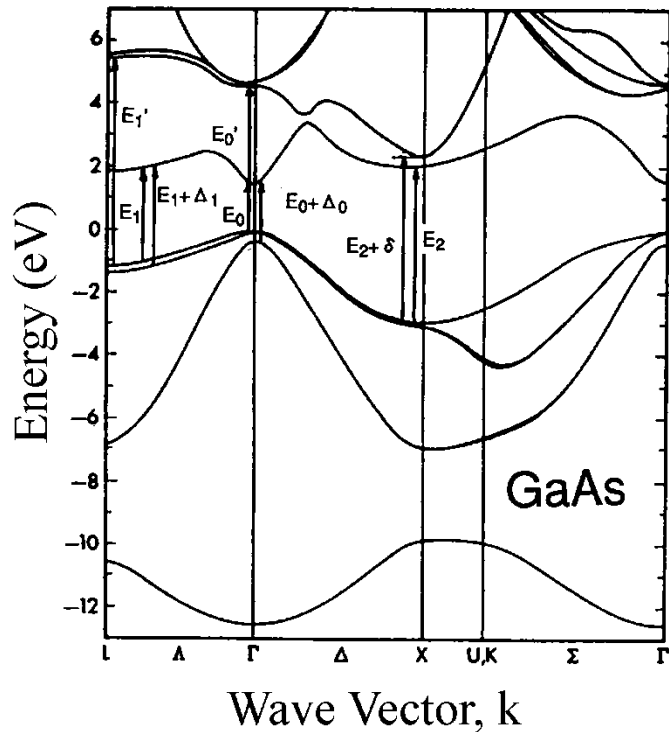
Metals: Free-carrier Absorption

- Metals have more electrons than needed for bonding (covalent bonds = sharing electrons).
- Electric wave causes “free” electrons to move.
- When electrons collide with nearby atoms wave energy is lost as heat.



Semiconductors: Electronic Transitions

- Electrons in energy bands.
- Gap between valence-conduction band.
- If light (photon) provides enough energy electron may excite to higher state.

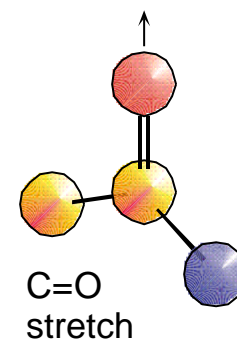
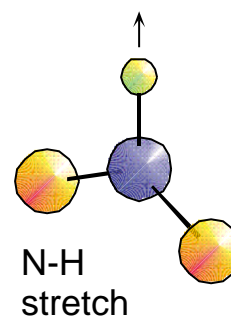
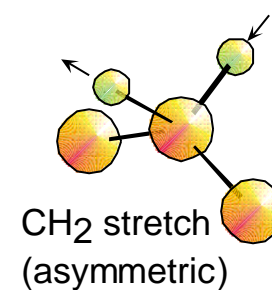
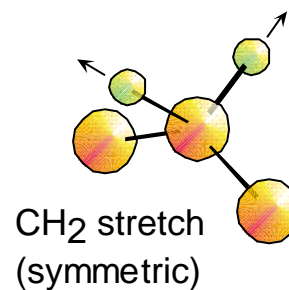
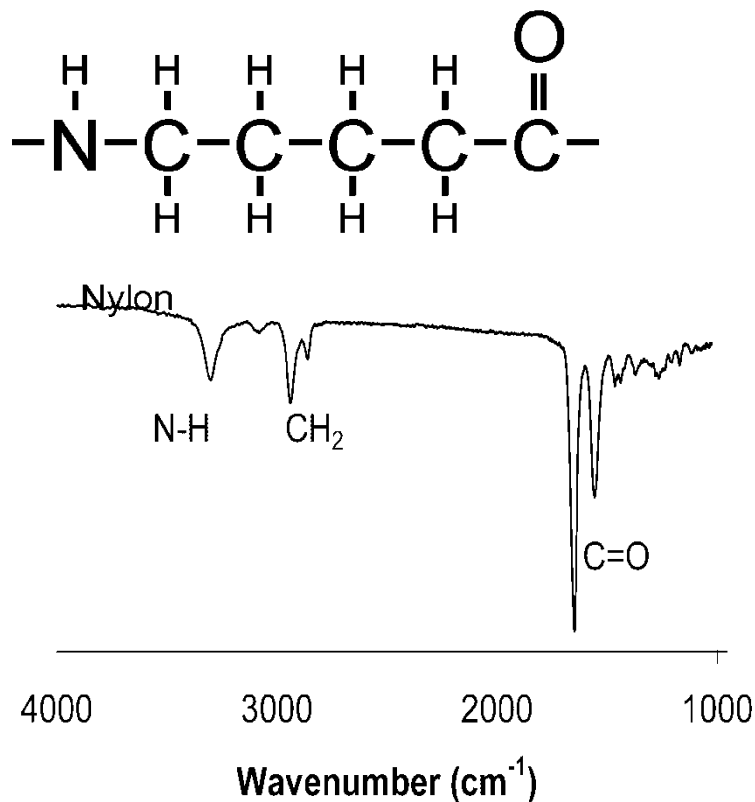


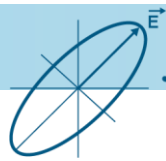
- Real materials have complicated energy bands.
- See lots of sharp structures in optical constants.

S. Adachi, *Optical properties of crystalline and amorphous semiconductors*, Kluwer Academic Publishers, Boston (1999).

Infrared Absorption: Molecular Vibrations

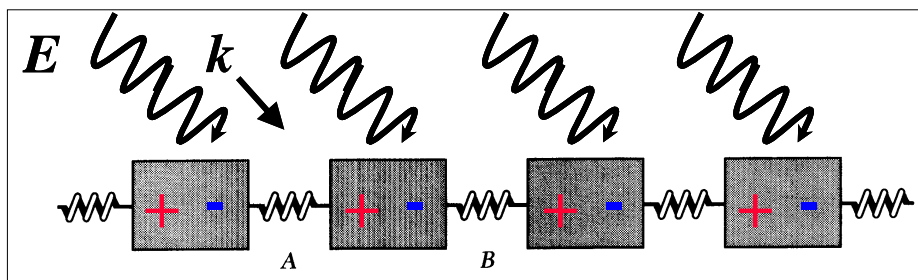
- Infrared light has low energy. Can vibrate molecules (stretching, bending, twisting, rotating).



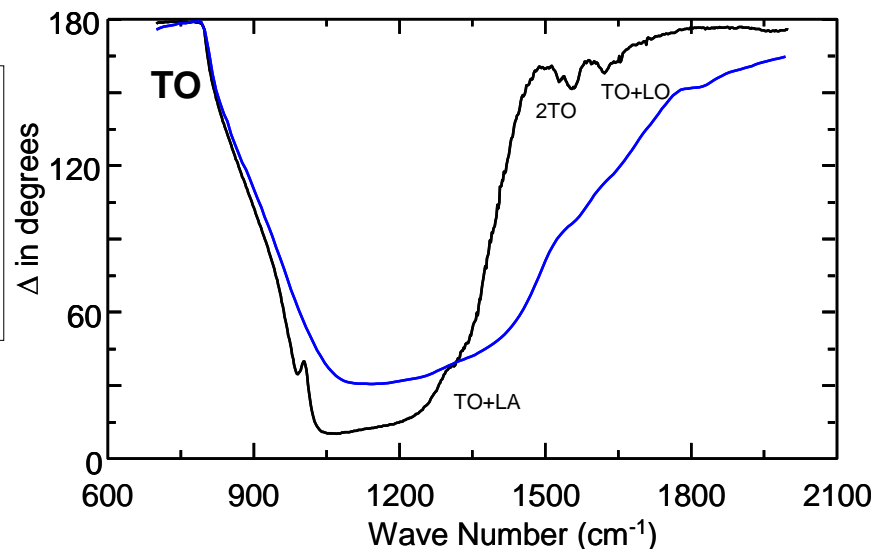


Infrared Absorption: Crystal Lattice Vibrations

- **Electric Field causes crystal lattice to vibrate.**
 - Longitudinal (LO) or Transverse (TO) Optical “Phonons”.



M. Schubert, 2002



T.E. Tiwald et al., *Thin Solid Films*, 313-314 (1998) 661.

Optical Constants

- **Complex Refractive Index:**

$$\tilde{n}(\lambda) = n(\lambda) \pm ik(\lambda)$$

$$E(z, t) = E_0 \exp[i(\omega t - \mathbf{K}z + \delta)]$$
$$\mathbf{K} = \frac{2\pi}{\lambda} (n - ik)$$

Describes what material does to light wave.

- Slows down, wavelength changes, refraction, extinction.

Alternatively...

- **Complex Dielectric Function:**

$$\varepsilon(\lambda) = \varepsilon_1(\lambda) \pm i\varepsilon_2(\lambda)$$

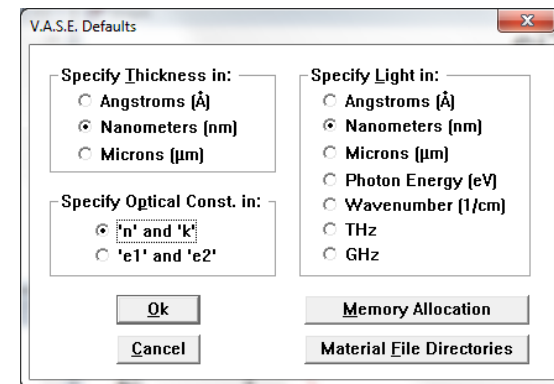
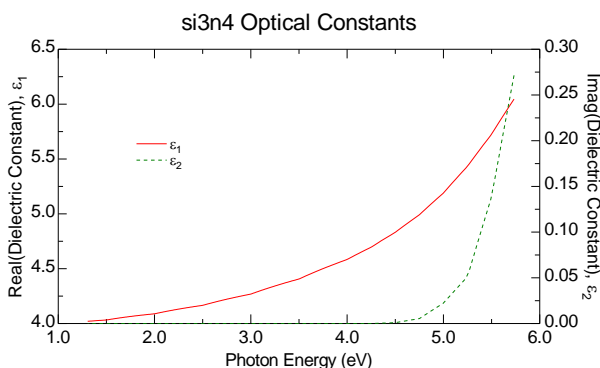
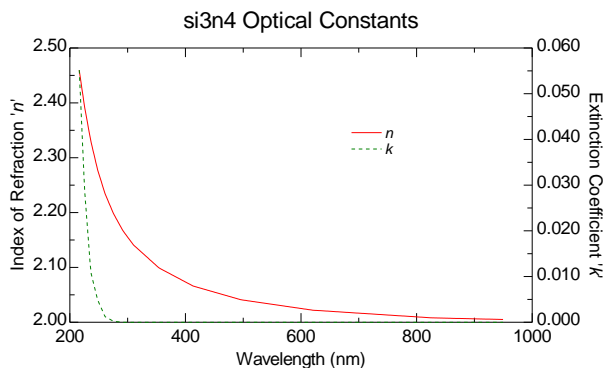
$$\mathbf{D} = \varepsilon \mathbf{E}$$
$$\varepsilon = \varepsilon_0(1 + \chi), \quad \varepsilon_r = \frac{\varepsilon}{\varepsilon_0}$$

Describes what wave does to material.

Graphing Optical Constants in WVASE.

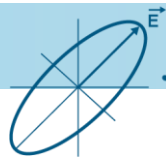
Using **Graph Window**.

- **Select Data: “Current Layer (Opt. Const.)”**
- Note position of current layer arrow “>” next to layer.
- Select **Global, then “Defaults”**
- Change plot to “e1 & e2” vs eV.



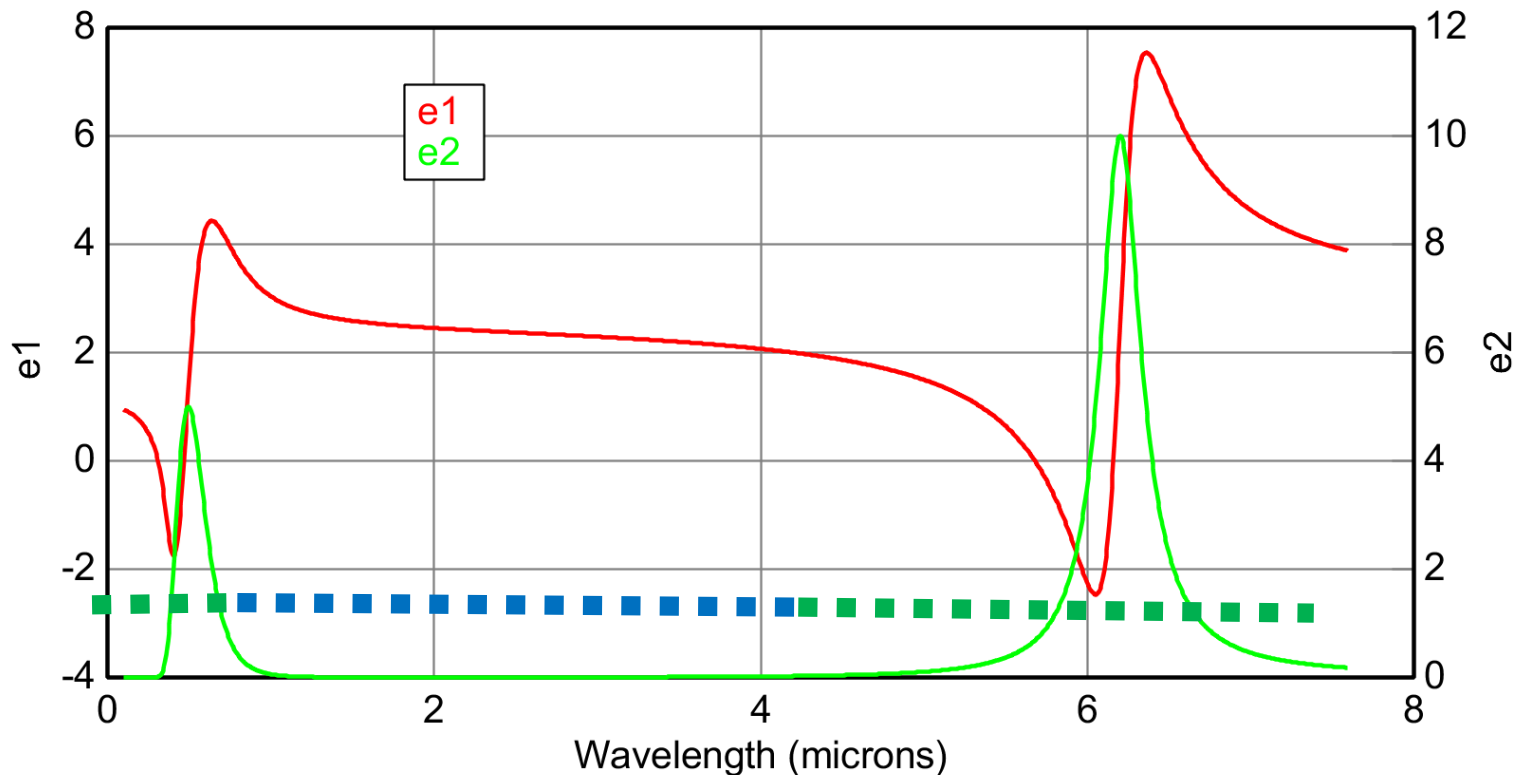
Learning Outcomes:

- Graphing layer optical constants in WVASE.
- Understand “Current layer”.
- Changing defaults settings.



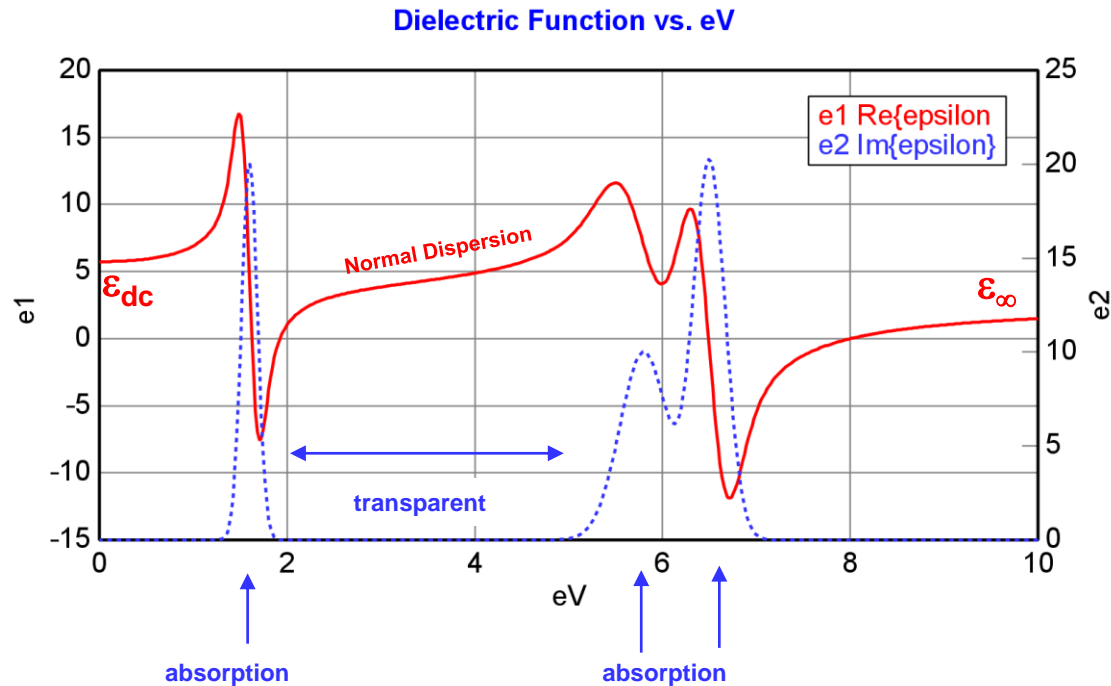
Dispersion: Wavelength Dependence

- Optical Properties vary with wavelength.
- Transparent regions (**normal** dispersion).
- Absorbing regions (**anomalous** dispersion).

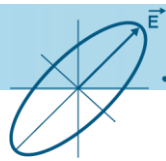


The Dielectric Function $\epsilon(\omega)$

- The Dielectric Function $\epsilon(E)$ or $\epsilon(\omega)$, is the Dielectric Polarization as a function of Energy (or Frequency).



- Regions of transparency, and regions of absorption.
- **Where do these features come from?**



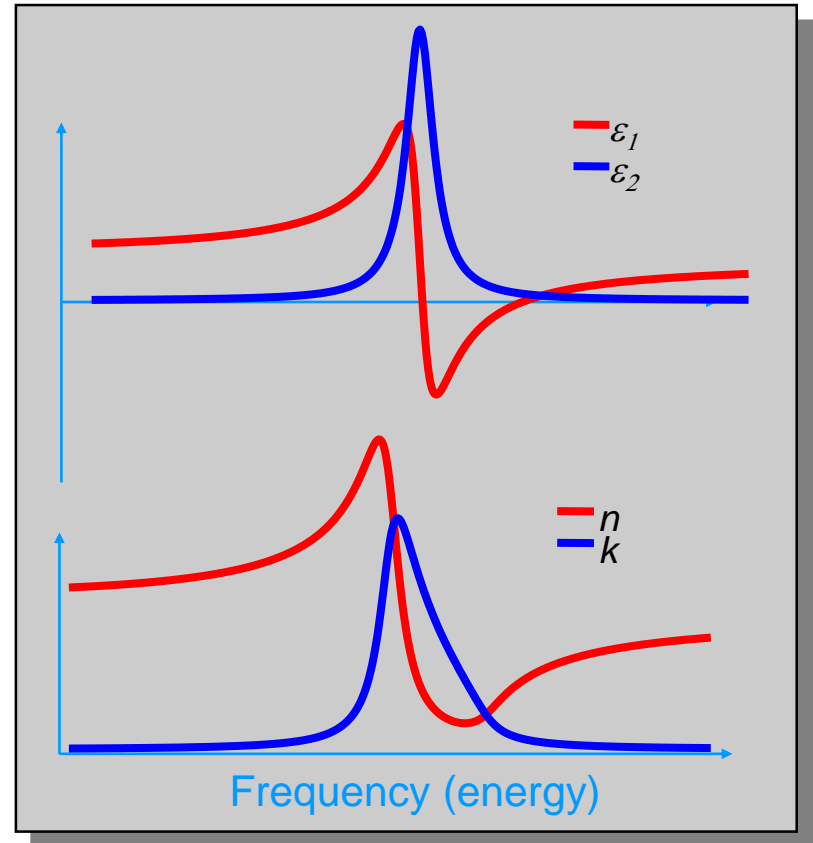
Kramers-Kronig Relation

- Real and imaginary parts depend on each other.
- Optical constants **must** satisfy KK-relation to be physical.
- “Bumps make wiggles”...the shape of n & k curves are related.

$$\varepsilon_1(\omega) = 1 + \frac{2}{\pi} P \int_0^{\infty} \frac{\omega' \varepsilon_2(\omega')}{\omega'^2 - \omega^2} d\omega'$$

$$\varepsilon_2(\omega) = -\frac{2\omega}{\pi} P \int_0^{\infty} \frac{\varepsilon_1(\omega') - 1}{\omega'^2 - \omega^2} d\omega'$$

P means “principal part”



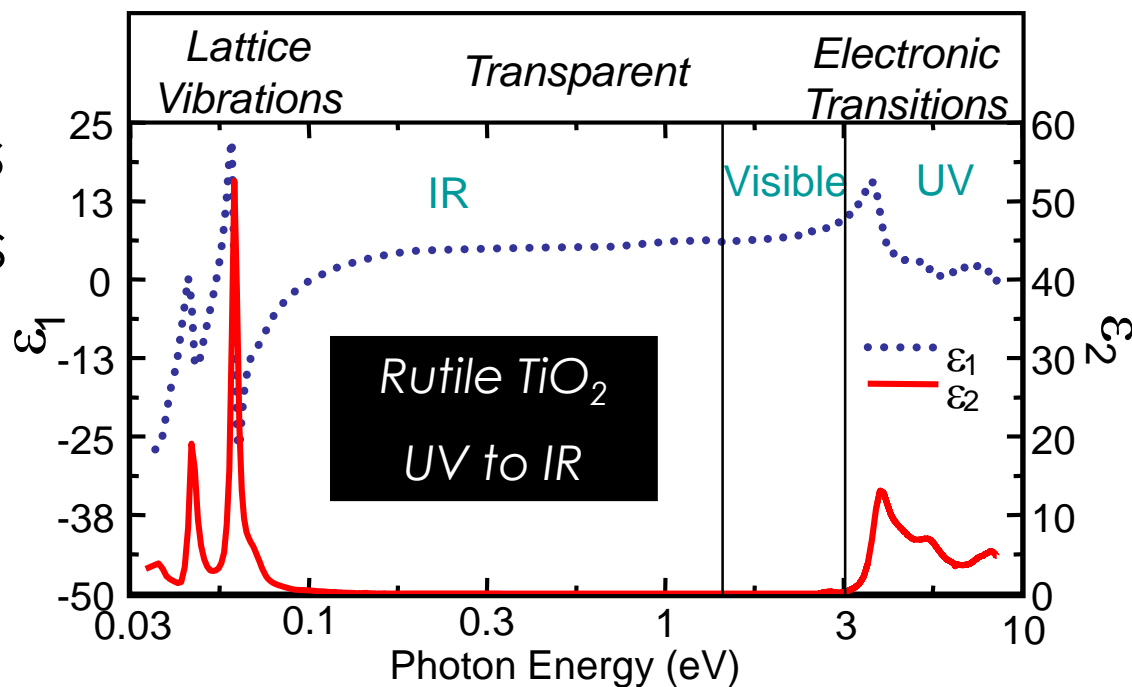
Integral equation relates area under ε_2 to shape of ε_1 and vice-versa.

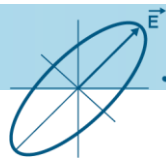
Absorbing Regions

Absorbing regions occur in different parts of the spectrum.

Absorptions have different shapes, depending on cause.

- Free-carriers
- Electronic Transitions
- Molecular Vibrations
- Lattice Vibrations





Dispersion Models: Practical Use.

- Equations used to describe the optical functions versus wavelength.

- Transparent Materials:

- Cauchy, Sellmeier models.

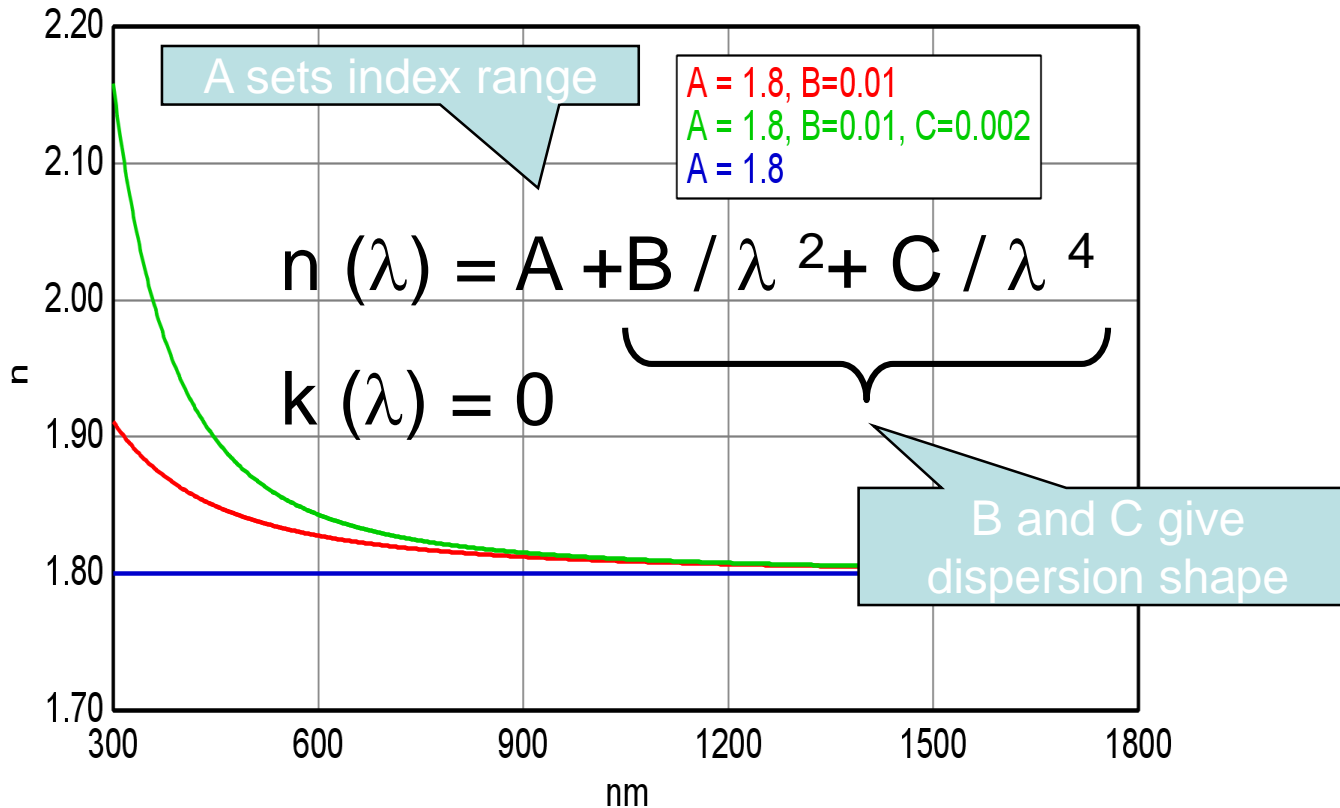
- Absorbing Materials:

- Large variety of Oscillator Models:
- Lorentz, Drude, Gaussian, Tauc-Lorentz, etc.
- All available within Genosc.mat layer!

Transparent Materials: Cauchy Dispersion Equation

- Describes index (n) as a function of wavelength $n(\lambda)$.
- For transparent materials only ($k=0$ or very small).

Optical Constants of Cauchy Film



Augustin-Louis Cauchy
(1789-1857)

Using Model For Silicon Nitride on Silicon

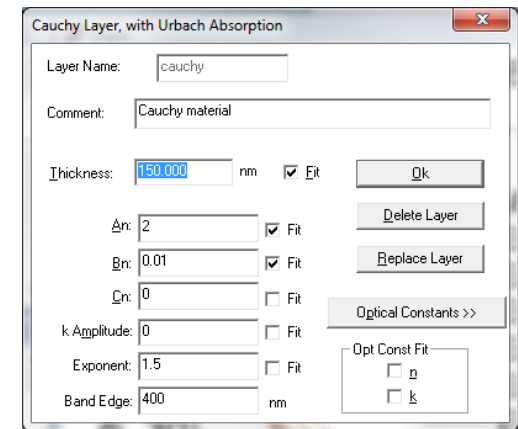
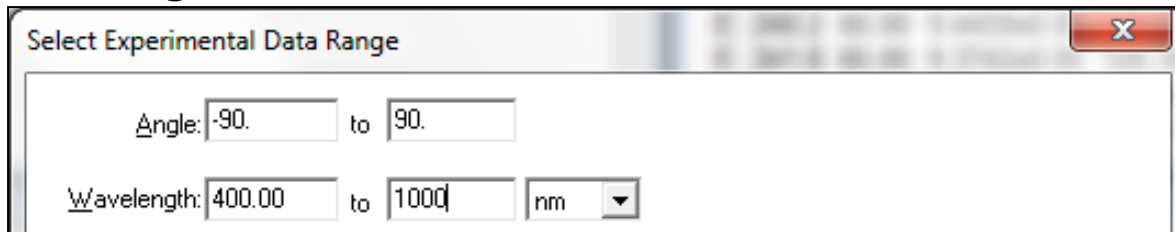
Select **Model Window**.

- Replace Si₃N₄ layer with Cauchy.mat
- Set $A_n=2$, $B_n=0.01$.

1	cauchy	150.000 nm
0	si_jaw	1 mm

Select **Experimental Data Window**.

- Range Select 400-1000 nm.



- Generate data.

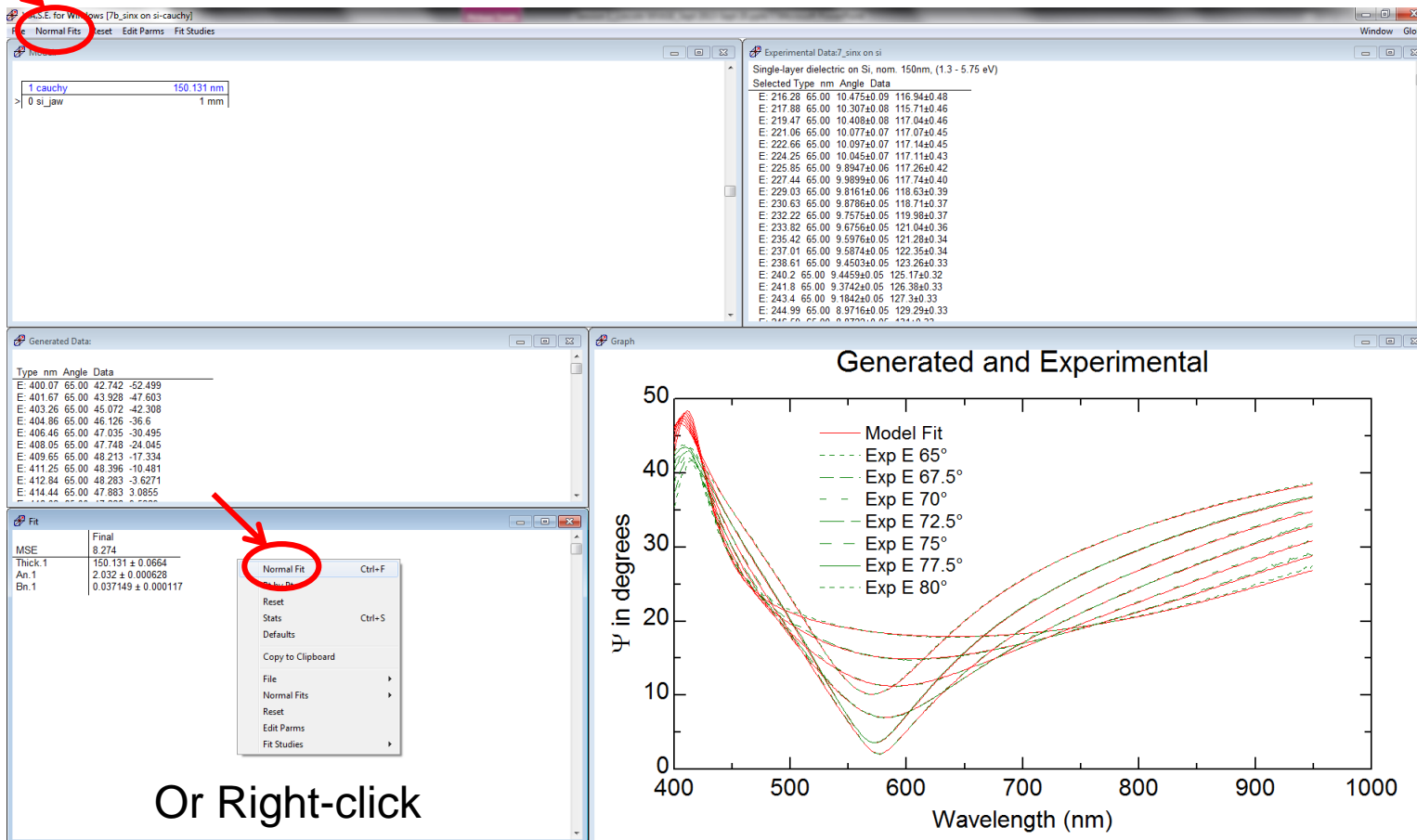
Learning Outcomes:

- Replacing layers.
- Define Fit parameters. Cauchy model for index.
- Select Experimental data range.

WVASE Fit Window

Used to optimize model by adjusting fit parameters

“Normal”
fit

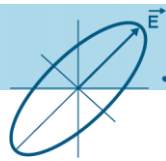


The screenshot shows the WVASE software interface. At the top, the 'Normal Fits' menu is highlighted with a red circle and an arrow. Below it, the 'Fit' window shows parameters for 'Thick.1' and 'An.1'. A red arrow points to the 'Normal Fit' option in the context menu. To the right, the 'Graph' window displays a plot of Ψ in degrees versus Wavelength (nm) from 400 to 1000 nm. The plot shows experimental data points (Exp E 65°, 67.5°, 70°, 72.5°, 75°, 77.5°, 80°) and a solid red line representing the 'Model Fit'. The 'Generated Data' window shows a table of experimental data points.

Type	nm	Angle	Data
E	400.07	65.00	42.742 -52.499
E	401.67	65.00	43.928 -47.603
E	403.26	65.00	45.072 -42.308
E	404.86	65.00	46.126 -36.6
E	406.46	65.00	47.035 -30.495
E	408.05	65.00	47.748 -24.045
E	409.65	65.00	48.213 -17.334
E	411.25	65.00	48.396 -10.481
E	412.84	65.00	48.283 -3.6271
E	414.44	65.00	47.883 3.0855

Or Right-click

**Perform a “Normal Fit” to start.
What’s going on below 450 nm? Beyond 850 nm?
How to improve this fit?**



Dispersion Models: Practical Use.

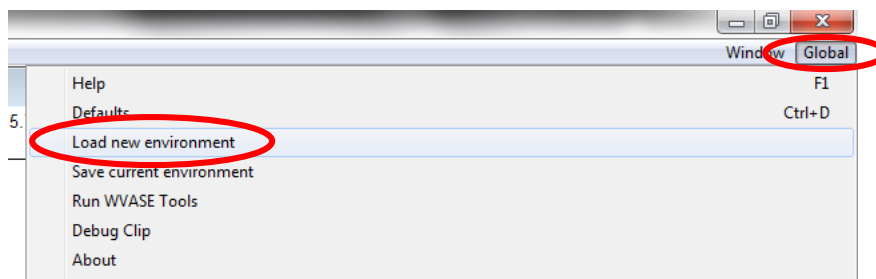
- Equations used to describe the optical functions versus wavelength.

- Transparent Materials:
 - Cauchy, Sellmeier

- Absorbing Materials:
 - Large variety of Oscillator Models:
 - Lorentz, Drude, Gaussian, Tauc-Lorentz, etc.
 - All available within Genosc.mat layer!

Silicon Nitride on Silicon Final Model Using Genosc.mat

- Select **Global**, then **“Load New Environment”**.



- **Open 7d_Sinx on Si-genosc.env**
- Examine Ψ and Δ data fits. Are the fits good?
- Click Genosc layer to open Window.
- Study oscillators and poles used for fit.

Learning Outcomes:

- Opening Environment Files.
- Study Genosc fit.

Silicon Nitride on Silicon Final Results

2	srough	1.877 nm
1	genosc	151.734 nm
0	si_jaw	1 mm

General Oscillator Layer

Name: genosc Comment: Generalized Oscillator Layer

Thickness: 151.734 nm Fit

Position (eV): Magnitude:

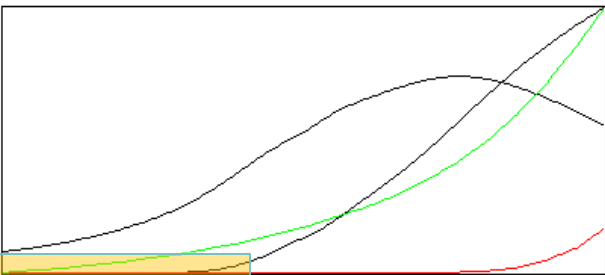
Pole #1: 9.3365 75.74

Pole #2: 0.001 0

ϵ_1 Offset: 1 Opt Const Fit

Egap: 0 n k

e1



Oscillator Parameters:

Active: Type: Style:

Gau: Gaussian .0: eV, A*Gauss(E,A,En,Br)

Amp En Br

1 3 0.2

e2

New Osc: Gau.0, Amp=1, En=3, Br=0.2

*1: C-L.0, Amp=31.608F, En=8.4768F, Br=8.7838F, Eg=3.4906F, Ep=1, Et=0, Eu=0.5

*2: Gau.0, Amp=0.46499F, En=3.7443F, Br=1.0119F

Graphing and Fitting Options

Ref. Material Fit to Ref. Reset

si3n4

1 - 6 by 0.025

Fit e2 only

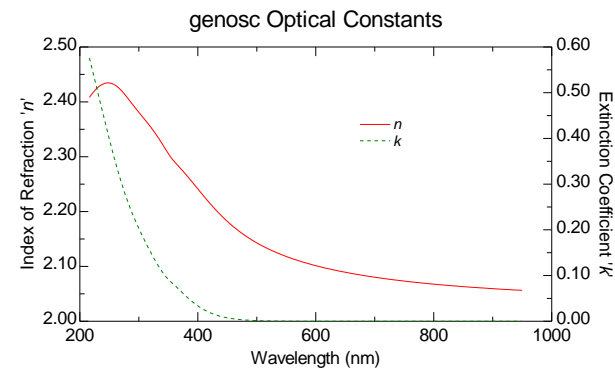
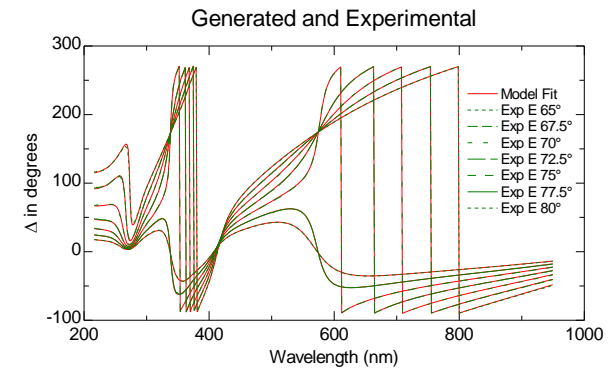
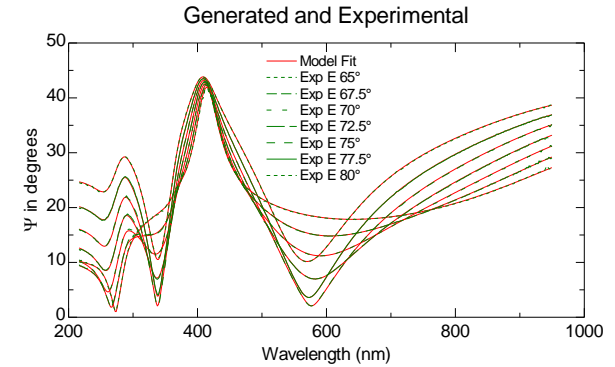
Fit Both

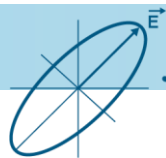
Fit e1 only

Restrict Params to Graph Range

Osc Up Osc Down Add Oscillator

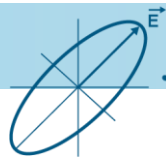
What is the role of e1 and e2 sections?





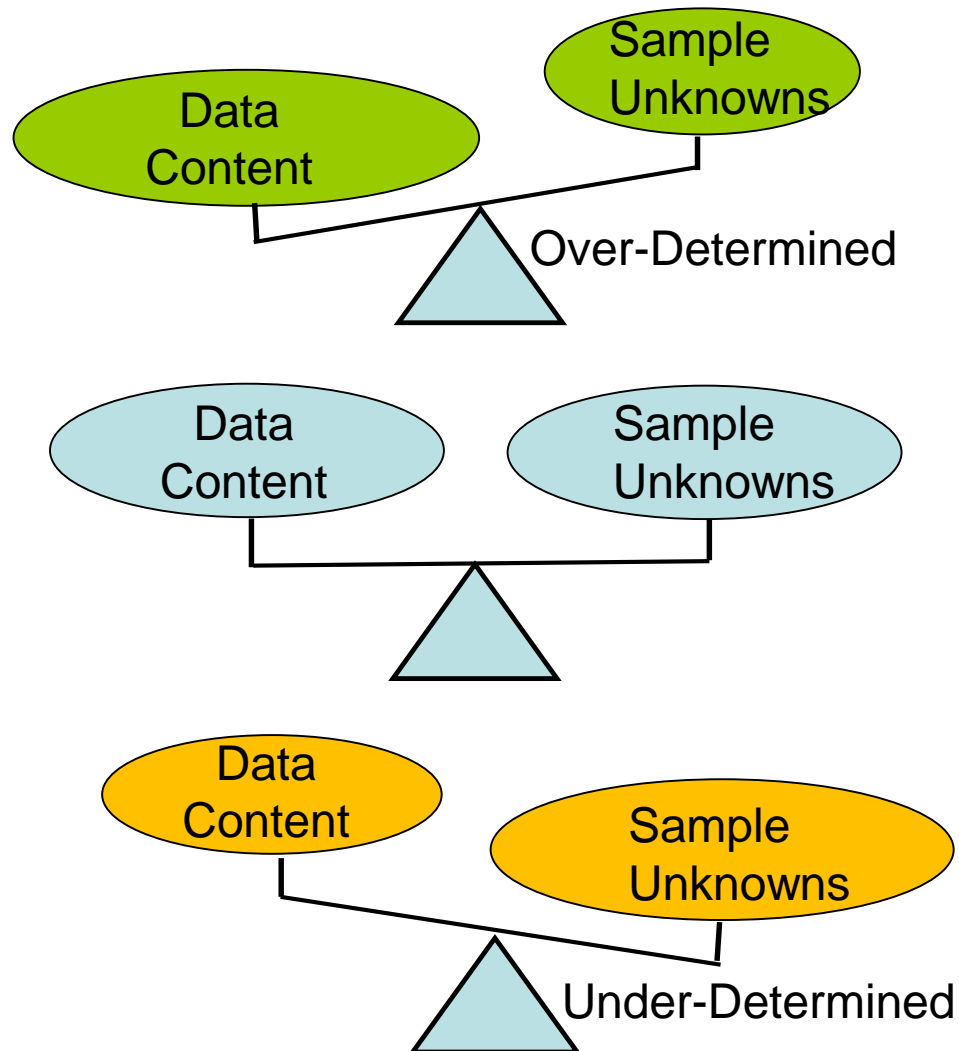
Ellipsometry Data Analysis

- Rest of this course...3 days.
- How to analyze data.
- Introduce some general concepts.



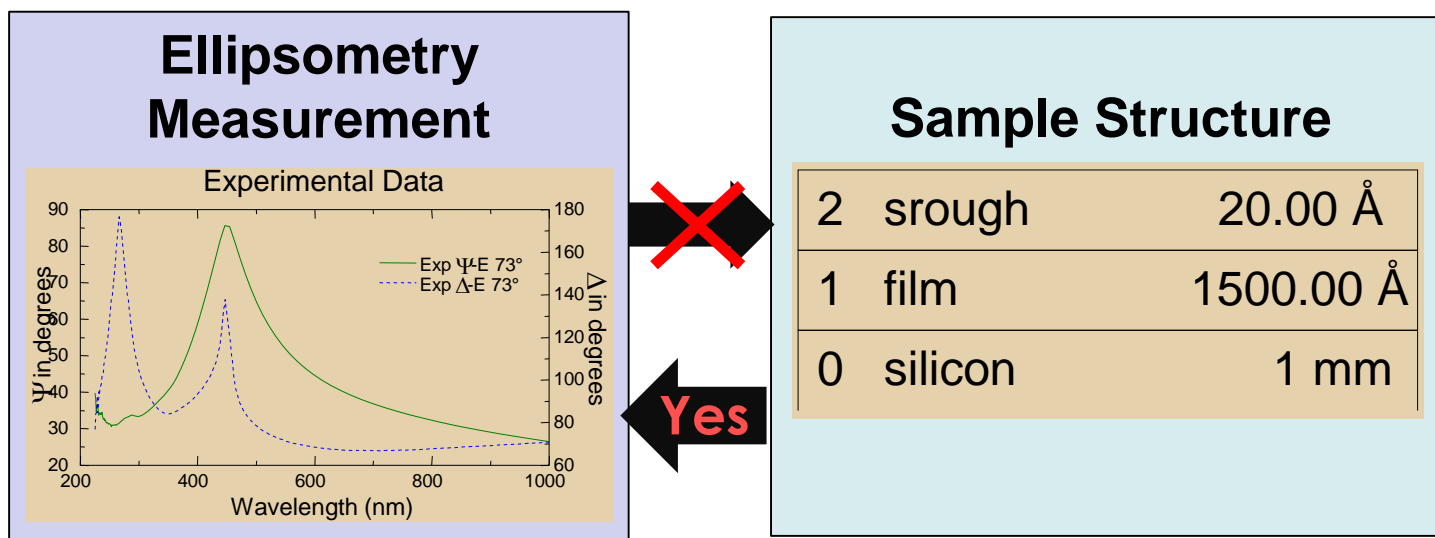
Data Content vs Sample Unknowns

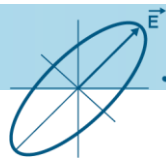
- **Ensure data contains information to solve all unknowns.**



Why Analyze Data?

- Ellipsometry measures two parameters: Ψ and Δ .
- Ψ and Δ are a function of film thicknesses and optical constants of materials under study.
- Desired **information must be extracted through a model based analysis** using optical physics.
- Inverse Problem:
 - **Result** is known instead of **Cause**.
 - Ellipsometry measures the “resulting” polarization change rather than sample properties that are the “cause”.

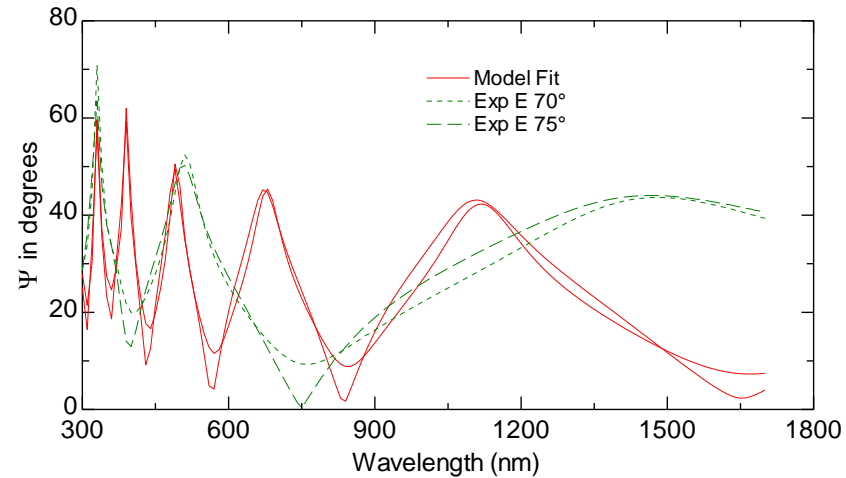




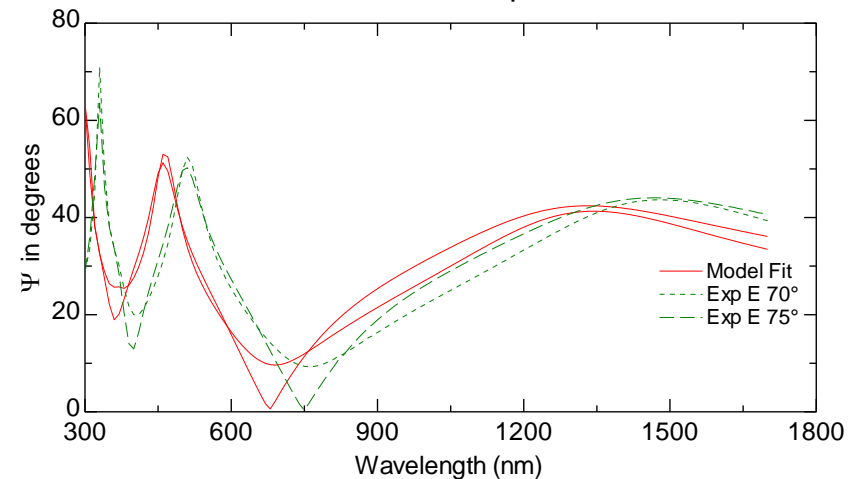
Generate Data From Model

- Calculate psi & delta from model.
- Compare to Experimental data.
- Adjust unknown (fit) parameters to get close to solution.

Generated and Experimental

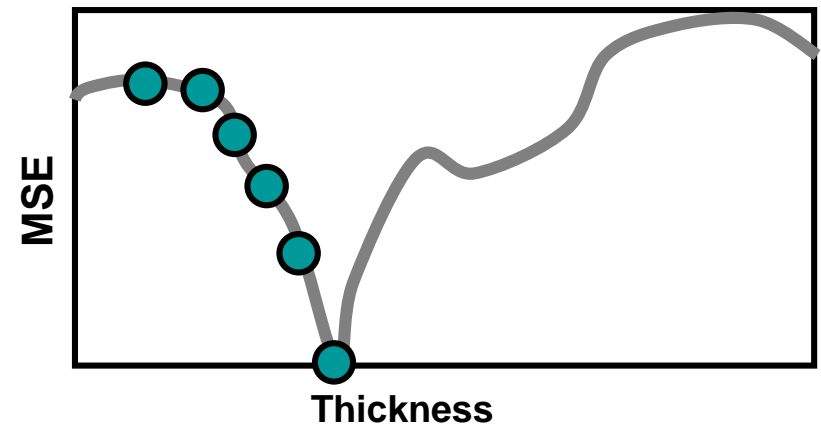
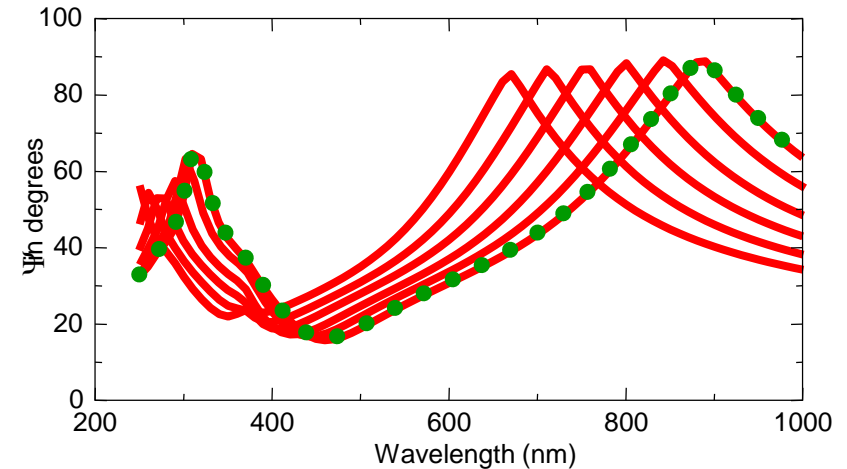


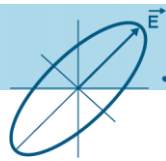
Generated and Experimental



Data Fitting

- Software adjusts “fit” parameters to find best match between model and experiment.
- MSE is Difference.





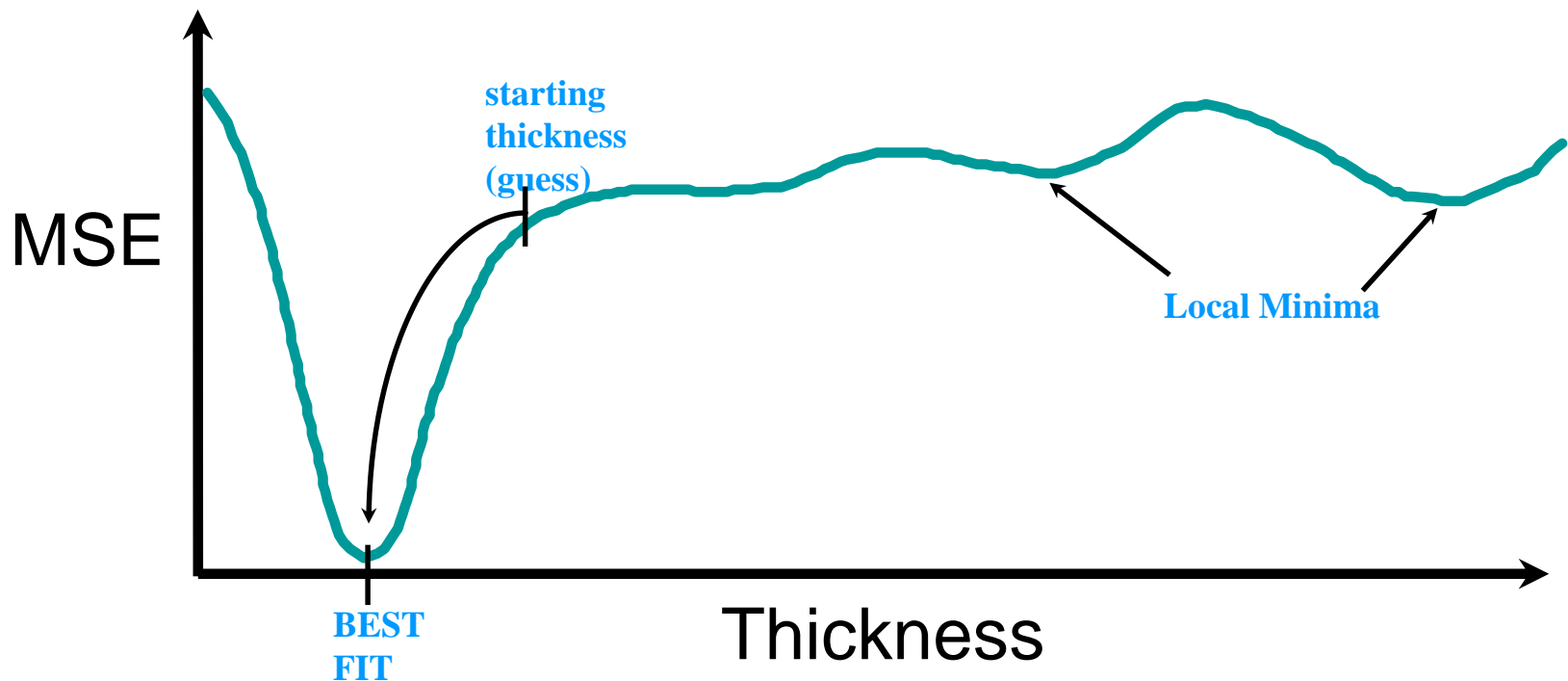
Data Fitting Algorithm

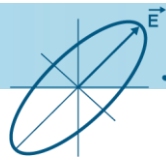
$$MSE = \frac{1}{2N - M} \sum_{i=1}^N \left[\left(\frac{\Psi_i^{\text{mod}} - \Psi_i^{\text{exp}}}{\sigma_{\Psi,i}^{\text{exp}}} \right)^2 + \left(\frac{\Delta_i^{\text{mod}} - \Delta_i^{\text{exp}}}{\sigma_{\Delta,i}^{\text{exp}}} \right)^2 \right] = \frac{1}{2N - M} \chi^2$$

- WVASE32 uses a Mean Squared Error (**MSE**) to quantify the difference between experimental and calculated model data.
- A smaller MSE implies a better fit.
- The MSE is weighted by the error bars on each measured data point, so noisy points are weighted less heavily.

Minimizing the MSE

- Levenberg-Marquardt algorithm used to quickly determine the minimum MSE (gives best fit to data).





Quality of Data Fit

Use our Physical Intuition!

When fit is complete resulting fit parameters must be evaluated for sensitivity and possible correlation.

- Compare experimental data with generated data.
- How low is MSE? Can it be reduced further by increasing model complexity?
- Are fit parameters physical?
- How large are 90% confidence limits?
- Check Correlation matrix. Are parameters correlated? Can some be turned off?

Correlation Matrix

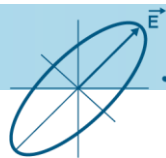
- Example of Correlation Matrix
 - matrix of two-parameter correlation coefficients calculated from the covariance matrix

Any off diagonal elements near +/-1 are correlated.

Correlation Matrix

	ThkUni	Thick.2	An.2	Bn.2	Cn.2
ThkUni	1.000	0.065	-0.091	0.028	-0.022
Thick.2	0.065	1.000	-0.680	-0.117	0.054
An.2	-0.091	-0.680	1.000	-0.530	0.515
Bn.2	0.028	-0.117	-0.530	1.000	-0.965
Cn.2	-0.022	0.054	0.515	-0.965	1.000

Correlated Parameters:
Cn.2 and Bn.2

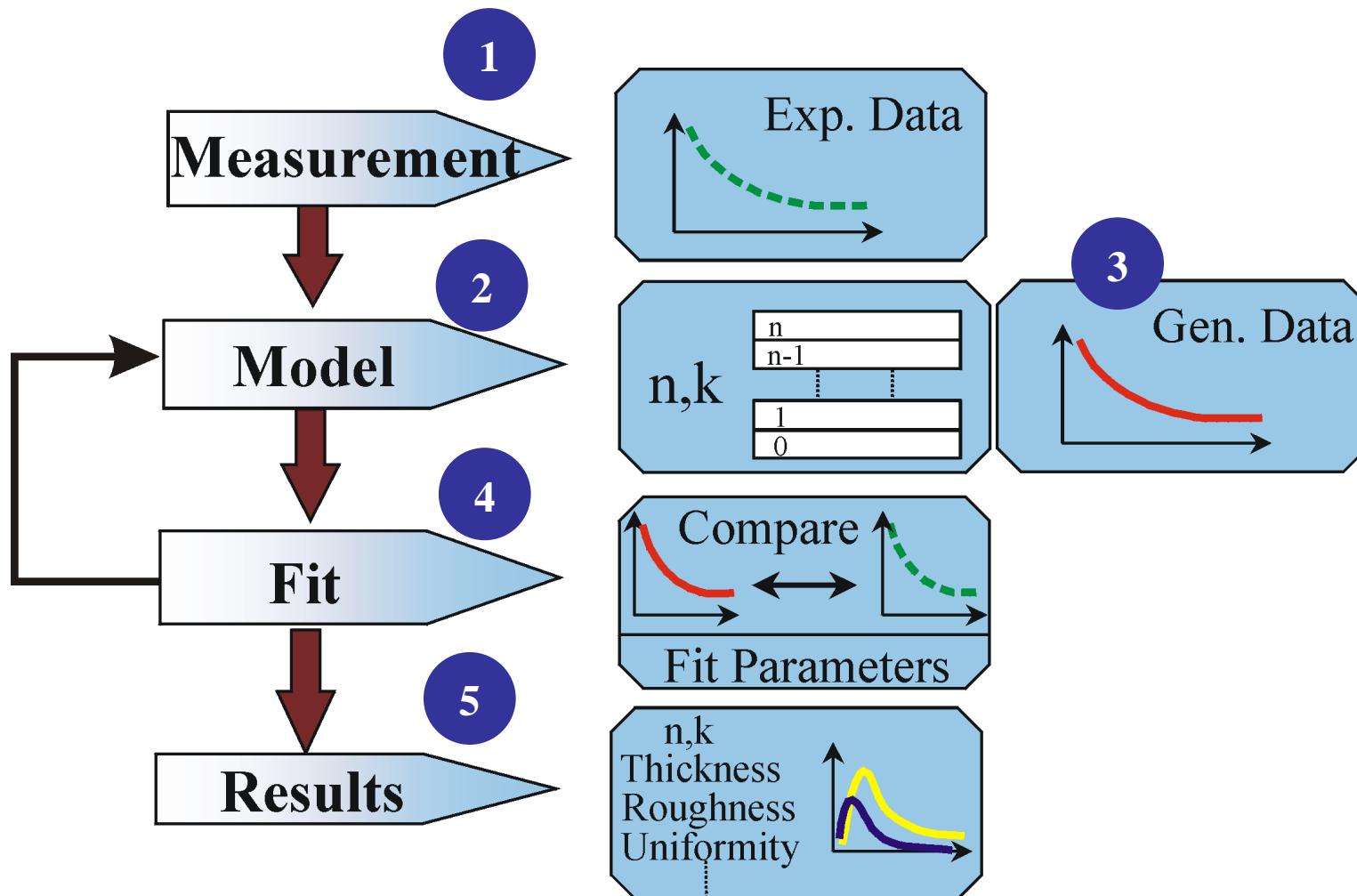


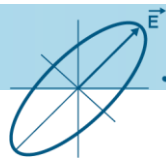
General Rules for Data Analysis

- Find the **simplest optical model** that fits Experimental Data.
 - User fewest fit parameters.
- **Verify uniqueness** of the model.
 - Check correlation matrix, and error bars on parameters.
- Optical 'constants' for materials are not always constant, and **quality of fit can only be as good as the optical constants** assumed in the model.
 - May need to fit n & k .



Data Analysis Flowchart





Summary – Session # 1

- **Introduction to Spectroscopic Ellipsometry**
 - Polarized light, Ellipsometry experiment.
- **Classification of Samples:**
 - Substrate, or coated,? Single-Layer, Multi-Layer?
 - Absorbing, Transparent, Semi-Absorbing?
 - Data Features: Spectral Interpretation.
- **Optical constants.**
 - Refraction, absorption, n & k . Dispersion.
 - Oscillator models, Cauchy, Lorentz, Gaussian, etc.
 - WVASE Genosc layer.
- **Fundamentals of WVASE.**
 - Basic software operation.

Lunch!

